QUANTUM EFFICIENCY OF ASTRONOMICAL CHARGE-COUPLED DEVICES FOR DEEPER EXPLORATION OF OUR COSMOS

A DISSERTATION

SUBMITTED IN PARTIAL FULFILLMENT OF THE **REOUIREMENTS FOR THE AWARD OF THE DEGREE OF**

MASTER OF SCIENCE

IN

PHYSICS

Submitted By:

ANMOL AGGARWAL & ASHI MITTAL 2K21/MSCPHY/55 & 2K21/MSCPHY/07

Under the supervision of

Prof. (Dr.) NITIN K. PURI Dr. GEORGE M. SEABROKE



DEPARTMENT OF APPLIED PHYSICS

DELHI TECHNOLOGICAL **UNIVERSITY** (Formerly Delhi College of Engineering) Bawana Road, Delhi-110042



DEPARTMENT OF SPACE & CLIMATE PHYSICS

UNIVERSITY COLLEGE LONDON Holmbury St. Mary, Dorking, Surrey United Kingdom- RH5 6NT

May, 2023

QUANTUM EFFICIENCY OF ASTRONOMICAL CHARGE-COUPLED DEVICES FOR DEEPER EXPLORATION OF OUR COSMOS

DELHI TECHNOLOGICAL UNIVERSITY

(Formerly Delhi College of Engineering)

Bawana Road, Delhi-110042

CANDIDATE'S DECLARATION

We, Anmol Aggarwal & Ashi Mittal, Roll Nos. 2K21/MSCPHY/55 & 2K21/MSCPHY/07 respectively, students of M.Sc. Physics hereby declare that the project Dissertation titled "Quantum Efficiency of Astronomical Chargecoupled Devices for Deeper Exploration of our Cosmos", which is submitted by us to the Department of Applied Physics, Delhi Technological University, Delhi in the partial fulfilment of the requirement for the award of the degree of Master of Science, is original and not copied from any source without proper citation. This work has not previously formed the basis for the award of any Degree, Diploma Associateship, Fellowship or other similar title or recognition.

(And.

ANMOL AGGARWAL (2K21/MSCPHY/55)

Asherettai

ASHI MITTAL (2K21/MSCPHY/07)

Place: CERN, Switzerland

Date: 30th May 2023

Place: Delhi, India

Date: 30. May 2023

DELHI TECHNOLOGICAL UNIVERSITY

(Formerly Delhi College of Engineering)

Bawana Road, Delhi-110042

CERTIFICATE

I hereby certify that the Project Dissertation titled "Quantum Efficiency of Astronomical Charge-coupled Devices for Deeper Exploration of our Cosmos" which is submitted by Anmol Aggarwal & Ashi Mittal, Roll Nos. 2K21/MSCPHY/55 & 2K21/MSCPHY/07, Department of Applied Physics, Delhi Technological University, Delhi in partial fulfilment of the requirement for the award of the degree of Master of Science, is a record of the project work carried out by the students under our supervision. To the best of our knowledge, this work has not been submitted in part or full for any Degree or Diploma to this University or elsewhere.

Dam 30/5723

Prof. (Dr.) Nitin K. Puri SUPERVISOR

Professor Department of Applied Physics Delhi Technological University

G. M. Jeabrokey

Dr. George M. Seabroke CO-SUPERVISOR

Principal Research Fellow Mullard Space Science Laboratory Department of Space and Climate Physics University College London

Place: Delhi, India

Date: 30 May 2023

Date: 30 May 2023

Place: Newbury, United Kingdom

ABSTRACT

When one looks up at the sky and counts the number of stars and observes constellations, they are not only appreciating the beauty of the universe but doing an astronomer's job as well. Astronomy is the oldest science that humans have dealt with, and it is rather the simplest science that can be done with the naked eye. Our quest to understand the nature of our existence started with the simple observation of celestial objects. With time humans were able to solve a lot of such mysteries and as we move on to the next job, it becomes more complex. In today's astronomical scenario, this quest is driven by the advancement in the technology used for observing our universe.

Charge-coupled devices (CCDs) are the backbone of all space study missions today, such as Gaia, Hubble Space Telescope, James Webb Telescope, etc. They are the basic piece of machinery used by any space mission to capture the light in space and help us create images that can be studied on Earth. Their functionality is what makes them an imperative instrument whose efficiency needs to be as high as possible. Hence this project is focused on finding ways to enhance the quantum efficiency of Gaia Astrometric Field (AF) CCDs by altering some of their structural parameters.

CCDs lose a lot of incident photons due to optical losses. To reduce the loss anti-reflection (AR) coatings are applied on the substrate. Currently, hafnium dioxide (HfO₂) is being used as an AR coating for the Gaia AF CCDs. Through our studies, we contemplated alternative AR coatings that could increase the QE of the CCDs. Aluminium oxide (Al₂O₃), zinc sulphide (ZnS), zirconium dioxide (ZrO₂), and tantalum pentoxide (Ta₂O₅) are some promising materials that have been selected and tested by us for the Gaia AF CCDs.

Further, gallium nitride (GaN) has been analysed as an alternative to silicon for its use in broadband astronomical CCDs. The optical and electronic performance of GaN and silicon CCD pixel models have been compared for this purpose.

Simulations have been conducted using the SILVACO TCAD software to test these coatings on the Gaia pixel structure. The Monte Carlo method has been implemented by SILVACO for these simulations. ATLAS module of the SILVACO software is employed for the model.

Upon contemplation, two AR coatings (Ta₂O₅ and ZrO₂) turn out to produce better results than HfO₂. They give better QE towards the lower end of the Gaia AF CCDs' operational spectrum (from 0.330 μ m to 0.575 μ m) and prove to be better AR coatings for broadband astronomical CCDs. GaN also proves to be substantially better than silicon for use in such devices. These studies will open new avenues for understanding the evolution of the Milky Way and our universe.

ACKNOWLEDGEMENT

There are a lot of people who helped us out from time to time and aided in the completion of this work. We are extremely grateful to all of them but first and foremost we would to express our immense gratitude towards our dissertation supervisor and our mentor, Prof. (Dr.) Nitin K. Puri. He has been there for us every step of the way to guide us through any kind of problem. He kept our morals high and taught us how to walk on the path of research at Delhi Technological University. His innovative pedagogy must be specially highlighted which not only enabled us to complete this work but also prepared us for our future research and life challenges.

We are extremely thankful to our dissertation co-supervisor, Dr. George M. Seabroke. He has been an incredible support throughout our research work. His expertise and experience in the subject matter provided us with invaluable insights and helped enhance our research quality. It is his work on the Gaia AF CCDs that inspired us to work in this direction.

We also extend our in-depth gratitude towards our friend and role model Dr. Ritika Khatri. She supported us in keeping our spirits high even when the times were very distressful. We would also like to thank our laboratory members and friends, Nikita Jain, Hemant Kumar Arora and Sunil Kumar, for their constant support and understanding.

Finally, we would like to thank our parents and family members whose blessings and constant affirmation made it possible for us to be capable enough to work at Delhi Technological University.

Ashi Netlal

ASHI MITTAL

ANMOL AGGARWAL

CONTENTS

| | | Title | Page No. |
|-------------|-----------|---------------------------------------|----------|
| C | andida | te's Declaration | iii |
| C | ertifica | te | iv |
| A | bstract | | V |
| A | cknowl | ledgement | vii |
| Т | able of | Contents | viii |
| L | ist of Ta | ables | xi |
| L | ist of Fi | igures | xii |
| L | list of S | ymbols, Abbreviations, and | xvi |
| N | omencl | lature | |
| 1. I | ntroduc | ction | 1 |
| 1.1 | Struct | ure of Charged Coupled Devices (CCDs) | 1 |
| 1.2 | Opera | tion of CCDs | 3 |
| 1.3 | Types | of CCDs | 4 |
| 1.4 | Impor | tance of CCDs in Astronomy and | 5 |
| | Astrop | physics | |
| 2. P | Perform | ance of CCDs | 8 |
| 2.1 | Quant | um Efficiency (QE) | 8 |
| | 2.1.1 | Internal Quantum Efficiency | 8 |
| | 2.1.2 | External Quantum Efficiency | 9 |
| 2.2 | Factor | rs Affecting Quantum Efficiency | 9 |
| | 2.2.1 | Real Refractive Index | 9 |
| | 2.2.2 | Complex Refractive Index | 10 |
| | 2.2.3 | Thickness of the Substrate Material | 11 |
| 2.3 | Concl | lusion | 11 |
| 3. A | nti-Ref | flection (AR) Coatings | 12 |
| 3.1 | Select | ing the materials for AR coatings | 12 |
| | 3.1.1 | Reflectivity | 13 |
| | 3.1.2 | Refractive Index Matching | 14 |
| | 3.1.3 | Absorption Coefficient | 18 |

| 3.2 | 2. Conclusion | 19 |
|-------------|---|----|
| 4. | Benchmarking of the Gaia Astrometric Field | 20 |
| | CCD pixel structure using SILVACO | |
| 4.1 | Gaia Pixel Structure | 20 |
| 4.2 | 2 Modelling Using SILVACO TCAD | 22 |
| 4.3 | Comparison with reported External Quantum | 26 |
| | Efficiency | |
| 4. 4 | Conclusion | 27 |
| 5. | Study of the QE of the Gaia AF CCD pixel | 28 |
| | model with several AR coatings | |
| 5.1 | With Hafnium Dioxide | 28 |
| 5.2 | 2 With Zinc Sulphide | 29 |
| 5.3 | With Aluminium Oxide | 30 |
| 5.4 | With Zirconium Dioxide | 31 |
| 5.5 | With Tantalum Pentoxide | 33 |
| 5.6 | 6 Conclusion | 35 |
| 6. | Analysis of gallium nitride as an alternative | 38 |
| | to silicon for astronomical CCDs | |
| 6.1 | Importance of imaginary refractive index | 38 |
| 6.2 | 2 Suitability of GaN for broadband | 40 |
| | astronomical CCDs | |
| 6.3 | Simulation and calculations for the GaN CCD | 40 |
| | pixel structure | |
| 6.4 | Comparison of the GaN CCD model with the | 41 |
| | Gaia AF CCD model | |
| 6.5 | 5 Conclusion | 44 |
| 7. | Conclusion and future scope of this work | 45 |
| Ref | erences | 47 |
| Dec | laration and Certificate | 51 |
| List | of Publications | 53 |
| Acc | eptance Proofs | 54 |

| Journal Index Proof | 55 |
|--------------------------------------|----|
| Plagiarism Report | 57 |
| Accepted Research Article | 58 |
| Communicated Research Article | 67 |

LIST OF TABLES

| S.No. | Table No. | . Title of the Table | |
|--------|------------|--|-----|
| 5.110. | Table INO. | Title of the Table | No. |
| 1. | Table 4.1 | The thickness and doping densities of different layers in the AF CCD pixel structure. | 23 |
| 2. | Table 4.2 | List of theoretical and experimental constants. | 24 |
| 4. | Table 5.1 | Percentage increment and decrement in the QE of the Gaia AF CCD with different AR coatings as compared to the HfO ₂ AR coating. | 35 |

LIST OF FIGURES

| S. No. | Fig. | Title of the Figure | Page No. |
|--------|----------|---|-----------|
| | No. | The of the Figure | I age 100 |
| 1. | Fig. 1.1 | 1.1 Schematic of a basic MOS structure | |
| 2. | Fig. 1.2 | Schematic of (a) SCCD; (b) BCCD | 2 |
| 3. | Fig. 1.3 | Charge transfer mechanism in a CCD | 3 |
| 4. | Fig. 1.4 | Front-illuminated CCD (Left); Back-illuminated CCD (Right) | 5 |
| 5. | Fig. 3.1 | Reflectivity of the CCD surface without any AR coating and with different AR coatings | 13 |
| 6. | Fig. 3.2 | Comparison of the refractive index of HfO ₂ with the square root of the refractive index of silicon at different wavelengths | 14 |
| 7. | Fig. 3.3 | Comparison of the refractive index of ZnS with the square root of the refractive index of silicon at different wavelengths | 15 |
| 8. | Fig. 3.4 | Comparison of the refractive index of Al ₂ O ₃ with the square root of the refractive index of silicon at different wavelengths | 16 |
| 9. | Fig. 3.5 | Comparison of the refractive index of ZrO ₂ with the square root of the refractive index of silicon at different wavelengths | 17 |
| 10. | Fig. 3.6 | Comparison of the refractive index of Ta ₂ O ₅ | 18 |

| | | with the square root of the refractive index of | |
|-----|-----------------|--|----|
| | | silicon at different wavelengths | |
| | | The absorption coefficient of silicon (a) with AR | |
| 11. | Fig. 3.7 | coatings, (b) without AR coatings and (c) with | 19 |
| | | and without AR coatings | |
| | | The Gaia Focal Plane has 106 CCDs arranged in | |
| | | seven different rows. The red rectangles | |
| | | represent radial velocity spectrometers (RVS). | |
| | | The green and yellow rectangles depict blue and | |
| | | red photometers (BP and RP) respectively, while | |
| 12. | E :a 4 1 | the grey and black rectangles show wavefront | 22 |
| 12. | respe | sensors (WFS) and basic angle monitors (BAM) | |
| | | respectively. The light blue rectangles depict the | |
| | | most abundant i.e., AF CCDs and the dark blue | |
| | | rectangles are called sky mappers (SM). The SM | |
| | | and the WFS are also AF CCDs. The RVS and | |
| | | BAM have a construction similar to the RP. | 22 |
| 13. | Fig. 4.2 | Structure of a single pixel of the Gaia AF CCD | 73 |
| 13. | 1'1g. 4.2 | (all the measurements are in μ m) | 23 |
| | | The 2D Gaia AF CCD structure in the Across | |
| 14. | Fig. 4.3 | Scan (AC) direction as simulated in SILVACO | 25 |
| | | ATLAS. | |
| 15 | | Comparison of the actual EQE of the Gaia AF | 77 |
| 15. | Fig. 4.4 | CCDs and the EQE obtained from the | 27 |
| | | | |

| | 1 | | |
|-----|----------|--|----|
| | | simulations | |
| 16 | Fig. 5.1 | QE of the Gaia AF CCD without and with an | 29 |
| 16. | Fig. 5.1 | HfO ₂ AR coating | 29 |
| | | QE of the Gaia AF CCD without an AR coating, | |
| 17. | Fig. 5.2 | with an HfO_2 AR coating, and with a ZnS AR | 30 |
| | | coating | |
| | | QE of the Gaia AF CCD without an AR coating, | |
| 18. | Fig. 5.3 | with an HfO ₂ AR coating, and with an Al ₂ O ₃ AR | 31 |
| | | coating | |
| | | QE of the Gaia AF CCD without an AR coating, | |
| 19. | Fig. 5.4 | with an HfO_2 AR coating, and with an ZrO_2 AR | 32 |
| | | coating centred at 0.65 µm | |
| | | QE of the Gaia AF CCD without an AR coating, | |
| 20. | Fig. 5.5 | with an HfO_2 AR coating, and with an ZrO_2 AR | 33 |
| | | coating centred at 0.625 µm | |
| | | QE of the Gaia AF CCD without an AR coating, | |
| 21. | Fig. 5.6 | with an HfO ₂ AR coating, and with an Ta_2O_5 AR | 34 |
| | | coating centred at 0.65 µm | |
| | | QE of the Gaia AF CCD without an AR coating, | |
| 22. | Fig. 5.7 | with an $HfO_2 AR$ coating, and with a $Ta_2O_5 AR$ | 35 |
| | | coating centred at 0.625 µm | |
| | | The real (n) and imaginary refractive indices (k) | |
| 23. | Fig. 6.1 | of (a) silicon, (b) silicon carbide (SiC), and (c) | 39 |
| | | gallium nitride (GaN) in the wavelength range | |
| | | of 0.2 μm to 0.8 μm. | |

| 24. | Fig. 6.2The potential variation of the silicon Gaia AF CCD pixel model | | 42 |
|-----|---|---|----|
| 25. | Fig. 6.3 | The potential variation of the GaN pixel model | 42 |
| 26. | Fig. 6.4 | Comparison of the IQE and EQE of the GaN model with the silicon pixel model when they are simulated (a) Without any AR coatings, (b) with only silicon model with an HfO ₂ coating, and (c) with GaN model with an Al ₂ O ₃ AR coating and silicon model with an HfO ₂ AR coating | 43 |

LIST OF SYMBOLS, ABBREVIATIONS, AND

NOMENCLATURE

| S. No. | Acronym/Symbols | Full Form |
|--------|--------------------------------|-------------------------------|
| 1. | CCD | Charge-Coupled Device |
| 2. | MOS | Metal-Oxide-Semiconductor |
| 3. | SCCD | Surface Channel CCD |
| 4. | BCCD | Buried Channel CCD |
| 5. | СТІ | Charge Transfer Inefficiency |
| 6. | SiO ₂ | Silicon Dioxide |
| 7. | QE | Quantum Efficiency |
| 8. | AR | Anti-Reflection |
| 9. | IQE | Internal Quantum Efficiency |
| 10. | EQE | External Quantum Efficiency |
| 11. | R ₀ | Reflectivity |
| 12. | α | Absorption Coefficient |
| 13. | JWST | James Webb Space Telescope |
| 14. | HfO ₂ | Hafnium Dioxide |
| 15. | AF | Astrometric Field |
| 16. | Al ₂ O ₃ | Aluminium Oxide |
| 17. | ZnS | Zinc Sulphide |
| 18. | ZrO ₂ | Zirconium Dioxide |
| 19. | Ta ₂ O ₅ | Tantalum Pentoxide |
| 20. | ESA | European Space Agency |
| 21. | RP | Red Photometer |
| 22. | BP | Blue Photometer |
| 23. | RVS | Radial Velocity Spectrometers |
| 24. | WFS | Wavefront Sensors |
| 25. | BAM | Basic Angle Monitors |
| 26. | SM | Sky Mapper |
| 27. | J _{available} | Available Current Density |

| 28. | J _{source} | Source Current Density |
|-----|---------------------|----------------------------------|
| 29. | J _n | Electron Current Density |
| 30. | AC | Across Scan |
| 31. | ABD | Anti-Blooming Drain |
| 32. | Eg | Energy Gap of silicon |
| 33. | ε _r | Relative Permittivity of silicon |
| 34. | X | Electron Affinity of silicon |
| 35. | Т | Temperature |
| 36. | GaN | Gallium Nitride |
| 37. | SiC | Silicon Carbide |
| 38. | К | Kelvins |
| 39. | V | Volts |
| 40. | eV | Electron volts |
| 41. | nm | Nanometres |
| 42. | μm | Micrometres |
| 43. | AL | Along Scan |
| 44. | n | Real refractive index |
| 45. | k | Imaginary refractive index |
| 46. | λ | Wavelength |
| 47. | π | Pi |
| 48. | % | Percent |
| 49. | μs | Microseconds |
| 50. | FPA | Focal Plane Array |
| 51. | mm | Millimetres |
| 52. | 2D | 2 dimensions |
| 53. | cm ⁻³ | Per centimetre cube |
| 54. | > | Greater than |
| 55. | < | Less than |

CHAPTER 1

INTRODUCTION

A charge-coupled device (CCD) is used for digital image formation. It is based on the concept of photogeneration similar to that of the photoelectric effect [1-4]. While the photoelectric effect is generally exhibited by metals, the photogeneration in a CCD takes place inside a semiconductor.

In order to understand its working, one can use the concept of electrons and holes in semiconductors. When a photon is incident on the semiconductor surface it penetrates into the depletion region of the semiconductor substrate, if its energy is sufficiently high it then produces an electron-hole pair.

The construction, working, types, and relevance of CCD in the field of astronomy and astrophysics have been discussed in the subsequent sections in detail.

1.1 STRUCTURE OF A CHARGED COUPLED DEVICE

A CCD is a metal-oxide-semiconductor (MOS) based device, which utilises the field effect of electric potential [1, 4, 5]. It usually has a layer of

semiconductor and a conducting material separated by an insulating layer. The electrodes are not in direct contact with the semiconductor and the field effect properties of the electric potential are utilized [1, 4, 5]. The basic MOS structure can be seen in **Fig. 1.1**.

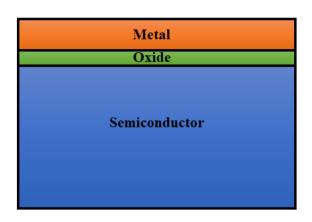


Fig. 1.1: Schematic of a basic MOS structure

The semiconductor layer of a CCD referred to as the substrate is either negatively doped, positively doped, or a p-n junction. A CCD that has only an n-type or p-type substrate is operated as a surface channel CCD (SCCD) [1, 6-8]. In an SCCD, the charge packet of the photogenerated charge carriers travels just underneath the insulating layer while being read out [1, 6-8]. If a p-n junction is used as a substrate in a CCD, then it is operated as a buried channel CCD (BCCD) [1, 7-9]. In a BCCD, the charge packet travels at a certain depth below the insulating layer while being read out [1, 7-9]. These CCDs have been represented in **Fig. 1.2**.

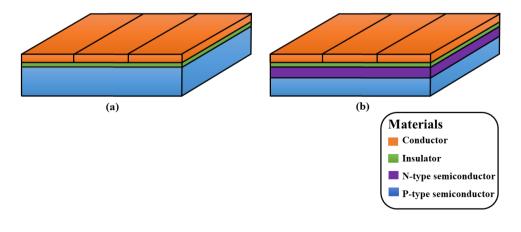


Fig. 1.2: Schematic of (a) SCCD; (b) BCCD

A BCCD is used for practical purposes because it offers two main advantages over an SCCD. An SCCD introduces charge transfer inefficiency (CTI) and dark current at the substrate-insulator interface [2, 3]. The substrate-insulator interface in an SCCD captures the charge carriers while they are being held by the potential on the electrode and releases them at a later time which causes CTI. It introduces dark current due to surface generation. These problems are nearly nonexistent in a BCCD [2, 3, 10].

Realistically, a CCD has several electrodes, which allow it to read out the photogenerated electrons by varying the applied potential on the electrodes [2]. Generally, a CCD has a silicon substrate, silicon dioxide (SiO₂) as an insulator and polysilicon electrodes. The reason for using SiO₂ as an insulator is that while fabricating such CCDs, the silicon substrate has to be simply oxidised to obtain this insulating layer.

1.2 OPERATION OF CCDs

A CCD uses electrical potential to generate a neutral region free of electrons and holes. This region is called the depletion region. When a photon with energy greater than the material bandgap is incident on this region it produces an electron-hole pair [1-4].

In the case of an SCCD the generated photoelectrons travel to the substrate-insulator interface because of the electrode potential [2, 3]. They are then read out with the help of a series of electrodes by varying their alternating potential [1-4]. This process can be understood in **Fig. 1.3**.

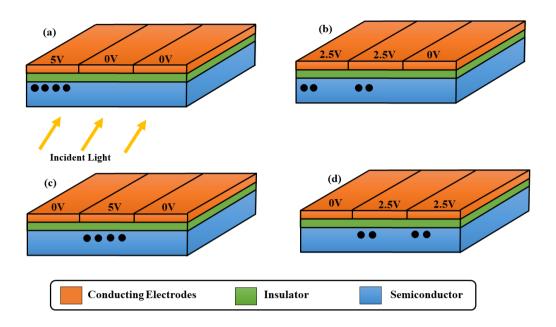


Fig. 1.3: Charge transfer mechanism in a CCD

In the case of a BCCD, the generated photoelectrons are held some distance below the substrate-insulator interface by reverse biasing the p-n junction. The same process, as is used for an SCCD, is followed by the BCCD to read out the charge packet produced.

1.3 TYPES OF CCDs

CCDs are broadly classified into two categories based on their illumination. Namely, front-illuminated and back-illuminated CCDs. The front-illuminated CCDs are those CCDs on which the light is incident from the electrode side, while the back-illuminated CCDs are illuminated from the substrate side [1-3].

While front-illuminated CCDs are easy to fabricate on a silicon wafer directly and are cheaper than back-illuminated CCDs, they offer many disadvantages. The electrodes of such CCDs absorb the blue and UV light almost completely hence they cannot be used to sense light of wavelengths shorter than 400 nm [2, 3]. They also offer very less quantum efficiency (QE) because of the reflections from the substrate-insulator interface. The back-illuminated CCDs do not offer any such problems.

The QE in the case of back-illuminated CCDs is much greater which enhances the precision of the photodetector. The only losses that occur in this case are due to the reflection from the substrate surface, which can be reduced by applying appropriate Anti-Reflection (AR) Coatings [2, 3, 11]. At times, the substrate of back-illuminated CCDs is made to be quite thin, which causes interference fringing. This problem has been solved but increasing the thickness of the substrate layer and applying suitable AR coatings [2, 3, 11]. Hence backilluminated CCDs are used for almost all applications in real life. Even though they are more expensive to fabricate, their performance justifies their cost. A schematic depicting the front and back-illuminated CCDs can be seen in **Fig. 1.4**.

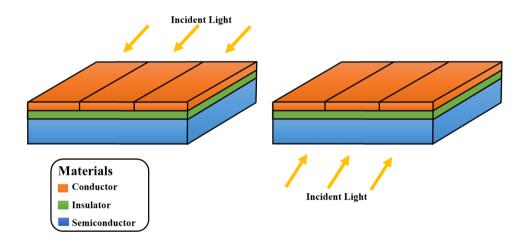


Fig. 1.4: Front-illuminated CCD (Left); Back-illuminated CCD (Right)

1.4 IMPORTANCE OF CCDS IN ASTRONOMY AND ASTROPHYSICS

Electromagnetic radiation which is light is one of the most important physical phenomena that has led to the exponential growth of our understanding of the universe and its physical and chemical properties. It is because the human eye is a natural detector of light, astronomy is the oldest science, which is built and driven by this physical entity. During the early years of astronomy, only heavenly bodies that are visible to the naked eye could be observed by astronomers. Due to the unavailability of complex optical devices, they were only able to obtain limited information from these bodies. For example, information about seasons and time.

The invention of optical telescopes in the 17th century enabled astronomers to observe lights which are not very intense. They offered higher light collecting capacity, resolution, etc. The first challenge to the theory of geocentrism was also brought with the help of the very first optical telescopes designed by Galileo Galilei [12].

With the advent of electronic techniques and devices the horizon of astronomy expanded far outside the visible range of light. For the first time astronomers were able to observe radiation invisible to the human eye such as radio waves, infra-red waves, etc.

Despite such advances in the field of astronomy and astrophysics, astronomers still faced the dilemma of storing their optical observations digitally to analyse them and obtain constructive results.

The northern lights or aurora borealis is the effect, which might make anyone feel ecstatic but is a pure nuisance from an astronomical point of view. It is produced by the interaction of the earth's atmosphere and high energy radiation from the space; hence such radiations are not able to reach the surface of the earth and can only be observed from space. Due to many such reasons, the astronomers were prompted to design electronic photodetectors.

These days, the CCD photodetectors form the backbone of astronomy [3]. Not only they allow the storage of optical astronomical data digitally, they also enable astronomers to make observations from the space. This development also made the study of high energy radiation such as ultra-violet and gamma rays possible which were otherwise hazardous to the human eye and can only be observed from space.

CCDs are employed extensively by all the space missions to obtain several types of astronomical data such spectroscopic information of stars and the interstellar medium, radial velocities, etc. Hence, CCDs can be classified as a cornerstone of modern-day astronomy.

CHAPTER 2

PERFORMANCE OF CCDs

The performance of CCDs is dependent on several factors. The primary factors that affect the performance are the refractive index and the thickness of the substrate material [3].

In this chapter, the QE of the CCDs, which is a standard parameter used to determine the performance of a CCD has been discussed. Usually, the higher the value of QE, the better the CCD.

2.1 QUANTUM EFFICIENCY

The QE is a quantitative parameter dependent on incident photons which is used to judge the performance of optical devices such as solar cells and CCDs. It has two types, internal and external [13]. Both are slightly different but are used extensively to describe the performance of optical devices. The value of QE can reach over 90% for back-illuminated CCD at certain wavelengths [2, 11].

2.1.1 Internal Quantum Efficiency

Internal Quantum Efficiency (IQE) is the ratio of the number of photons that enter the CCD to the number of photons incident on the substrate for a backilluminated CCD and on the electrodes for a front-illuminated CCD [13]. Its value never reaches the peak value of 100% as there are many losses involved, which are described in the following sections.

2.1.2 External Quantum Efficiency

External Quantum Efficiency (EQE) is the ratio of the number of photogenerated electrons in the CCD to the number of photons incident on the substrate for a back-illuminated CCD and on the electrodes for a front-illuminated CCD [13]. This is generally lower than the IQE for a given device because the electrons have to travel to the depletion region of the CCD to produce an electron-hole pair and they lose energy in this process. The read-out losses also account for the depreciation of the value of the EQE [13].

2.2 FACTORS AFFECTING THE QUANTUM EFFICIENCY

Several factors affect the QE of a CCD. They include numerous effects related to applied potential, the refractive index of the substrate, the crystalline purity of the substrate, operating temperature, doping density, thickness of the substrate, operating modes, radiation damage, etc. Although there are many more such phenomena that alter the QE, there are three major factors which affect the QE substantially. The three factors are the real refractive index, the complex refractive index, and the thickness of the substrate material.

2.2.1 Real Refractive Index

The refractive index of a material has two parts, real and complex. The real part of the refractive index symbolised as 'n', is commonly used in several equations such as the Snell's Law equation and to determine the speed of light in a material medium.

The real refractive index is essentially useful in calculating the reflectivity(R_0) of the substrate surface as per Eqn. 2.1.

Reflectivity
$$(R_0) = \left| \frac{n_1 - n_2}{n_1 + n_2} \right|^2$$
 (2.1)

Here n_1 refers to the real refractive index at a specific wavelength of the medium from which the light is incident, and n_2 is the real refractive index at a specific wavelength of the medium on which the light is incident.

Reflectivity is the measure of the amount of light of a specific wavelength that will be reflected off the surface of a material [14]. For instance, the reflectivity of 0.45 means that 45% of the incident light will not be able to enter the material's surface. This parameter should be essentially determined before selecting a material for a CCD. Since a low reflectivity will lead to enhanced performance of a CCD [2].

2.2.2 Complex Refractive Index

The complex refractive index of a CCD substrate is an extremely important parameter that is to be contemplated before selecting a material for a CCD. The complex refractive index symbolized as 'k', is also referred to as the imaginary refractive index. It is essential for calculating a prominent parameter called the 'Absorption Coefficient' using **Eqn. 2.2**.

Absorption Coefficient (
$$\alpha$$
) = $\frac{4\pi k}{\lambda}$ (2.2)

Here λ is the wavelength of the incident light. The absorption coefficient can be understood as the distance a photon can travel before it gets completely absorbed inside the material [15]. The larger the value of the absorption coefficient

of a material for the whole operating wavelength range, the better the material for a photodetector.

2.2.3 Thickness of the Substrate Material

It is very clear from the CCD design explained in the previous chapter that the thickness of the substrate can affect the energies of the photons reaching the depletion region. While travelling inside the substrate, a photon loses energy when it interacts with the electromagnetic fields produced by the atoms and the molecules of the material. To minimize this energy loss, the substrate should be thinned. A CCD substrate cannot be thinned beyond a certain limit as it will introduce interference fringing and make the depletion region thinner, which, in turn, will reduce the performance of a CCD. Hence the thickness of the CCD substrate is set such that its performance is optimised [3].

2.3 CONCLUSION

A CCD's performance is susceptible to many factors. Different studies and methods are adopted to optimise them so that a CCD can deliver the desired results. These methods include experimental testing and simulations. Ensuring that one gets optimum output from a CCD is essential for scientific fields such as astronomy. Astronomical missions (Gaia, James Webb Space Telescope (JWST), etc.) require very high-quality CCDs since they are required to interpret very lowintensity signals and they also do not get a lot of time to observe celestial objects.

CHAPTER 3

ANTI-REFLECTION (AR) COATINGS

Although silicon is a prominent material in the device-making industry, which is widely used for most semiconductor applications, it has a few drawbacks. One of the major drawbacks of silicon as a CCD material, is reflection loss. To reduce these losses and get the best possible QE of a CCD, AR coatings are applied. An AR coating is a thin layer of a high refractive index material which is applied on the substrate.

3.1 SELECTING THE MATERIALS FOR AR COATINGS

Any random material cannot be used as an AR coating. A material has to be rigorously analysed before it is used as an AR coating. The optical properties of a material govern three parameters, reflectivity, refractive index matching, and absorption coefficient which should be essentially contemplated.

Lesser [11] proposed several materials that can be used as AR coating for astronomical CCDs. Out of those materials hafnium dioxide (HfO₂) is an outstanding material for this purpose. It is currently being used as the AR coating for the Gaia astrometric field (AF) CCDs [16]. Other than HfO₂, aluminium oxide (Al₂O₃), zinc sulphide (ZnS), zirconium dioxide (ZrO₂), and tantalum pentoxide (Ta₂O₅) also turned out to be promising materials. The following sections describe how each of these materials satisfies the parameters listed above.

3.1.1 Reflectivity

The reflectivity of HfO₂, Al₂O₃, ZnS, ZrO₂, and Ta₂O₅ have been determined for the whole wavelength range of the Gaia AF CCDs using **Eqn. 2.1** and are plotted in a comparative graph in **Fig. 3.1**.

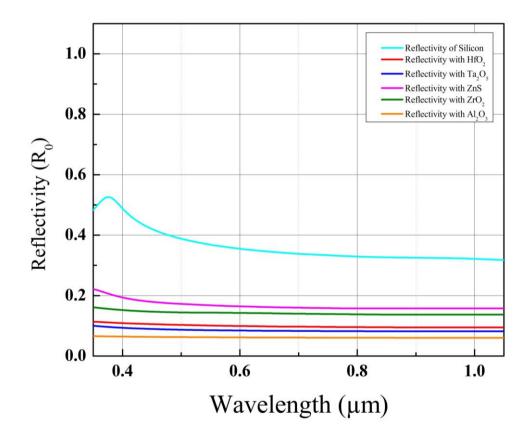


Fig. 3.1: Reflectivity of the CCD surface without any AR coating and with different AR coatings

The values of reflectivity reduce effectively after applying AR coatings. It is clearly understandable through **Fig. 3.1** that Al₂O₃ reduces the reflectivity to the lowest value and ZnS comparatively causes the least reduction in reflectivity of Gaia AF CCD. Ta₂O₅ decreases the reflectivity to a slightly lower value than HfO₂ while ZrO₂ reduces reflectivity to a slightly higher value than HfO₂, but the three of them are in close proximity.

3.1.2 Refractive Index Matching

The matching of the real refractive index of the AR coating material with that of the substrate material is crucial to determine a suitable AR coating for the CCD [11]. In practice, the square root of the refractive index of the substrate material (\sqrt{n}) should be in close approximation to the refractive index of the material in consideration at all respective wavelengths within the CCD operation range.

Fig. 3.2 shows a close matching between the refractive index of HfO_2 and the square root of the refractive index of silicon in the wavelength range of 330 nm -1050 nm. This suggests that HfO_2 can prove to be a good AR coating for the Gaia AF CCDs.

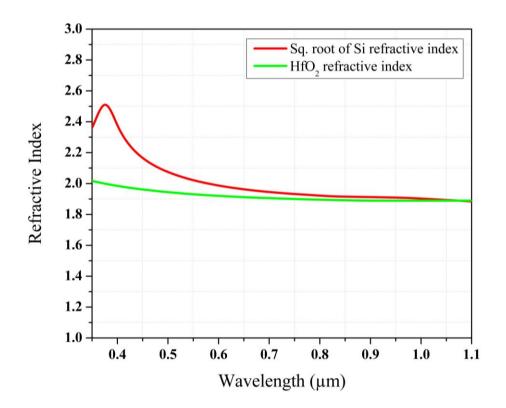


Fig. 3.2: Comparison of the refractive index of HfO₂ with the square root of the refractive index of silicon at different wavelengths

Figs. 3.3, 3.4, 3.5 and 3.6 depict that ZnS and Al₂O₃ show a relatively poor matching with the square root of the refractive index of silicon in the wavelength range of 330 nm -1050 nm, while ZrO₂ and Ta₂O₅ exhibit a strong matching. This suggests that HfO₂ can prove to be a good AR coating for the Gaia AF CCDs.

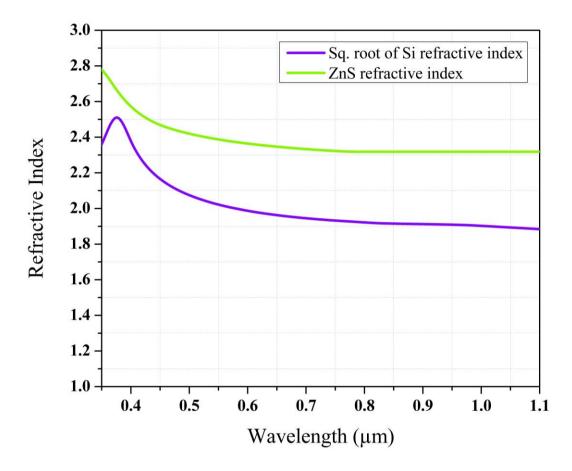


Fig. 3.3: Comparison of the refractive index of ZnS with the square root of the refractive index of silicon at different wavelengths

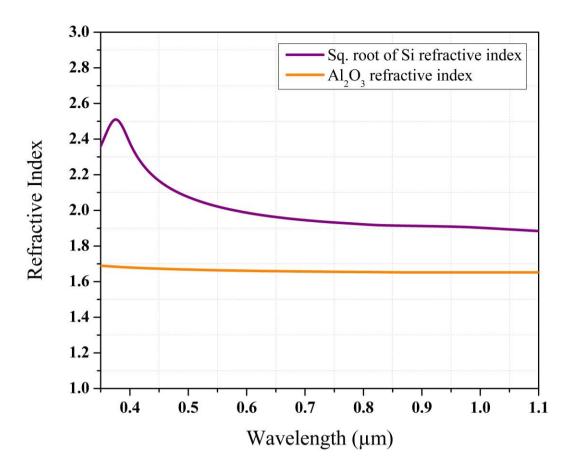


Fig. 3.4: Comparison of the refractive index of Al₂O₃ with the square root of the refractive index of silicon at different wavelengths

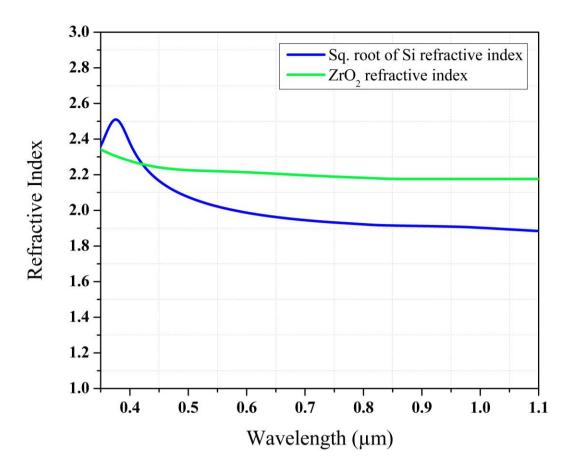


Fig. 3.5: Comparison of the refractive index of ZrO₂ with the square root of the refractive index of silicon at different wavelengths

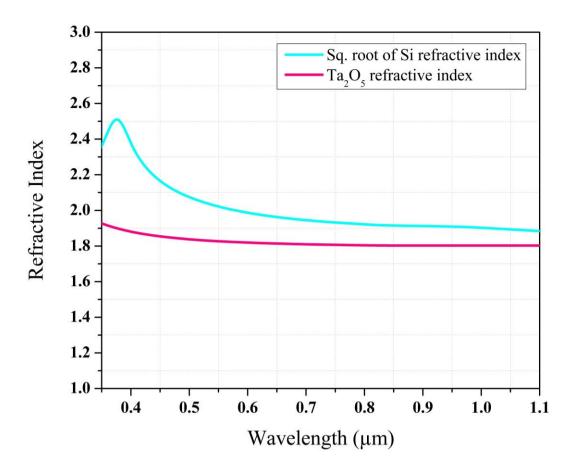


Fig. 3.6: Comparison of the refractive index of Ta₂O₅ with the square root of the refractive index of silicon at different wavelengths

3.1.3 Absorption Coefficient

The absorption coefficient of the substrate material plays a substantial role in determining the quantum efficiency of a CCD but is unaffected by an AR coating. This is evident from **Eqn. 2.2**, which shows that it is dependent only upon the imaginary refractive index of the substrate material. It is also depicted in the graphs presented in **Fig. 3.7**.

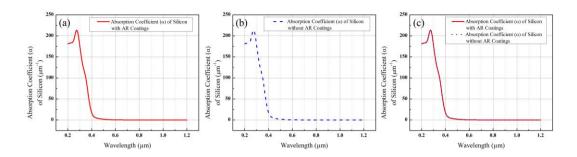


Fig. 3.7: The absorption coefficient of silicon (a) with AR coatings, (b) without AR coatings and (c) with and without AR coatings

Hence, in order to obtain a better absorption coefficient for a CCD one must change the substrate material itself.

3.2 CONCLUSION

Observing all the above presented data, we can conclude that HfO₂ satisfies all the conditions required to be a promising AR coating therefore it is currently being used by the Gaia AF CCDs and is providing very good QE. In order to search for alternative AR coating materials that can provide better results, other coatings need to satisfy the above-discussed conditions.

Al₂O₃ reduces the reflectivity largely, but its refractive index does not match the square root of the refractive index of silicon very well. This suggests that Al₂O₃ might give average results.

ZnS reduces the reflectivity to some extent and its refractive index moderately matches the square root of the refractive index of silicon. It can be deduced that ZnS can be used as an AR coating, but it might not give enhanced results as compared to HfO₂.

ZrO₂ and Ta₂O₅ reduce the reflectivity of silicon substantially and their refractive indices also match the square root of the refractive index of silicon very well, which helps us conclude that they might prove to be good AR coatings and provide improved results as compared to HfO₂. They might improve the QE of the Gaia AF CCD and quality of the collected data.

CHAPTER 4

BENCHMARKING OF THE GAIA ASTROMETRIC FIELD CCD PIXEL STRUCTURE USING SILVACO

The European Space Agency's (ESA) Gaia satellite contains 106 CCDs that are used for many photometric and astrometric measurements. The most abundant CCDs present on the Gaia focal plane are the AF CCDs, which are broadband, back-illuminated detectors [17]. Light is the core of optical astronomy; therefore, it is vital for astrometric devices to collect the maximum possible light. To increase the absorption of incident photons in the CCDs, AR coatings can be applied. To simulate the effects of various AR coatings on the Gaia AF CCDs, SILVACO TCAD software has been used.

SILVACO TCAD software is widely used to model electronic devices so that their performance can be tested and optimised to enhance their performance before they are physically designed. This software is based on Monte Carlo simulations and is used to predict the behaviour of optoelectronic devices in several conditions very well [18, 19].

4.1 GAIA PIXEL STRUCTURE

To enrich astronomy with more precise measurements, the ESA launched the Gaia Satellite in the L2 orbit in December 2013. Its two telescopes are keeping an eye on millions of stars, galaxies, and solar system objects to produce high-precision astrometric and spectroscopic measurements [17]. The continuous scan gives data sets that are repeatedly reduced to calculate the parallax, position, and proper motion of the celestial objects that are observed by the satellite [20]. The focal plane of the Gaia satellite contains 106 custom-built CCDs. These CCDs were designed and manufactured by e2v technologies, the United Kingdom [16].

Gaia CCDs were fabricated by e2v in three different variants -Astrometric Field (AF), red photometer (RP) and blue photometer (BP); each of these are optimised for different wavelength ranges [21]. The AF CCDs are built using silicon as a substrate with an AR coating which has a maximum photon absorption for light of 650 nm; this CCD has an extensive wavelength detection range of 330-1050 nm [22]. There are 78 AF CCDs on the Gaia Focal plane which are 16 µm thick [20]. The BP and RP are enhanced CCDs that have exceptional sensitivity towards the blue (330-680 nm) and red (640-1050 nm) regions of the light spectrum respectively. 7 BP CCDs present on the Gaia focal plane, have the maximum photon absorption for the light of 360 nm because of its AR coating [20]. Correspondingly, 7 RP CCDs have the maximum photon absorption for light of 750 nm [20]. These CCDs have an image area of 4500 lines × 1966 columns (here, lines and columns, refer to the rows and columns of the pixels of the CCD respectively) [21]. A schematic diagram of the arrangement of CCDs on the actual Gaia focal plane is shown in Fig. 4.1. The detectors are operating in the time delay and integration mode with a period of 982.8 μ s, which synchronises their line transfer rate with the satellite rotation rate [20, 21]. In Gaia parlance, line transfer means electrons being transferred in a row of pixels [20].

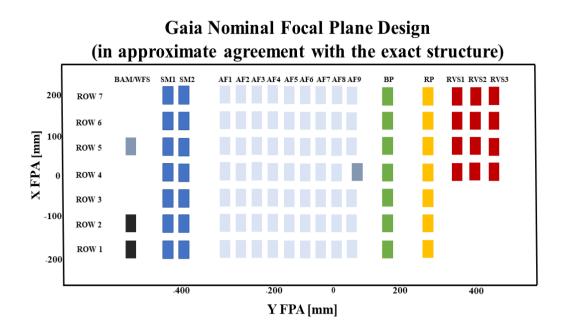


Fig. 4.1: The Gaia Focal Plane has 106 CCDs arranged in seven different rows. The red rectangles represent radial velocity spectrometers (RVS). The green and yellow rectangles depict BP and RP respectively, while the grey and black rectangles show wavefront sensors (WFS) and basic angle monitors (BAM) respectively. The light blue rectangles depict the most abundant i.e., AF CCDs and the dark blue rectangles are called sky mappers (SM). The SM and the WFS are also AF CCDs. The RVS and BAM have a construction similar to the RP.

4.2 MODELLING USING SILVACO TCAD

SILVACO TCAD is used to simulate several electronic and optical devices. It uses numerical methods for simulations so that the development and optimisation of such devices can be expedited. For simulating the effects of AR coatings on an optoelectronic device, the LUMINOUS and the ATLAS modules of this software can be used.

Since the Gaia AF CCDs are back-illuminated devices, the AR coatings are applied on the backside. Photons are also fired on this side in our simulations.

The operating voltage was set to 10 volts (V) as suggested by [23]. In SILVACO simulations the ratio of available current density ($J_{available}$) and source current density (J_{source}) gives the IQE of a device. The number of photoelectrons generated in a device can be determined using the electron current density (J_n).

For simulating the Gaia AF CCD pixel in SILVACO several structural parameters were required which were derived from [22-25]. The pixel structure of the CCD has three different faces, which is evident from **Fig. 4.2**. We simulated the structure in the across scan (AC) direction in 2D with a pixel size of 16 μ m × 30 μ m. The 16 μ m thickness of the pixel is subdivided into multiple layers, the details of which are summarised in **Table 4.1**.

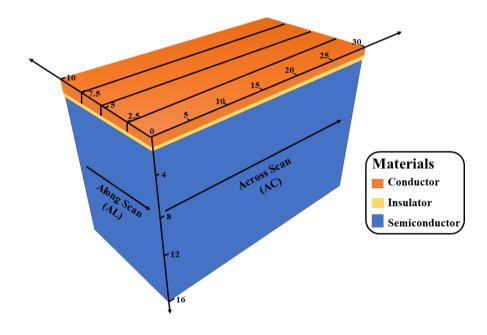


Fig. 4.2: Structure of a single pixel of the Gaia AF CCD (all the measurements are in μ m)

Table 4.1: The thickness and doping densities of different layers in the AF CCD pixel structure [23].

| S. Material Type | Thickness (μm) | Doping Density (cm ⁻³) |
|------------------|-------------------|---------------------------------------|
|------------------|-------------------|---------------------------------------|

| 1 | Polycrystalline silicon | Conductor | 0-0.5 | 0 |
|---|----------------------------|---------------|------------|-----------------------|
| 2 | SiO ₂ | Insulator | 0.5-0.63 | 0 |
| 3 | N-type silicon | Semiconductor | 0.63- 1.17 | 2.65×10^{16} |
| 4 | P-type silicon | Semiconductor | 1.17-16 | 1.3×10^{14} |

The length of the BC and the SBC runs from 4.5 to 29 μ m in the AC direction [25]. Another prominent feature of Gaia CCDs is an anti-blooming drain (ABD). The ABD, which is present on either side of the pixel in the AC direction is a shielding feature. It prevents the electrons from divulging into the adjacent pixel [24]. To simulate all these interesting features in SILVACO, the whole AF CCD image pixel was modelled with uniform doping as suggested by [23].

The Gaia AF CCDs work at a temperature of 163 K [22] to minimize the dark current, which is attributed to the false positive signals produced in the CCD due to the thermal energy of the electrons [3]. Therefore, to match our theoretical simulations with the experimental results reported by [16], we conducted our simulations at the same temperature.

In order to simulate the CCD pixel structure, the SILVACO ATLAS package uses some constants for the simulated materials that are handled internally. It uses the Monte Carlo method to model the structure. **Table 4.2** compares the experimental values of the constants with the values used during our simulations.

 Table 4.2: List of theoretical and experimental constants.

| S. | Name | of | the | Theoretical Values | Experimental Values |
|-----|---------|----|-----|--------------------|---------------------|
| No. | Constan | nt | | used in SILVACO | |
| | | | | ATLAS | |
| | | | | | |

| 1. | Energy gap of | 1.08 eV at 300 K | 1.12 eV at 300 K [26] |
|----|---|------------------|---------------------------|
| | silicon (Eg) | 1.11 eV at 163 K | |
| | | | |
| 2. | Relative | 11.8 at 300 K | 11.66 at 300 K [27] |
| | Permittivity of silicon (ε_r) | 11.8 at 163 K | |
| 3. | Electron Affinity | 4.17 eV at 300 K | 4.05 eV at 300 K [28, 29] |
| | of silicon (X) | 4.16 eV at 163 K | |
| 4. | Temperature (T) | 163 K | 163 K [22] |

Fig. 4.3 exhibits the simulated structure of the Gaia AF CCD pixel; the illustration was generated using the Tonyplot tool of the SILVACO software.

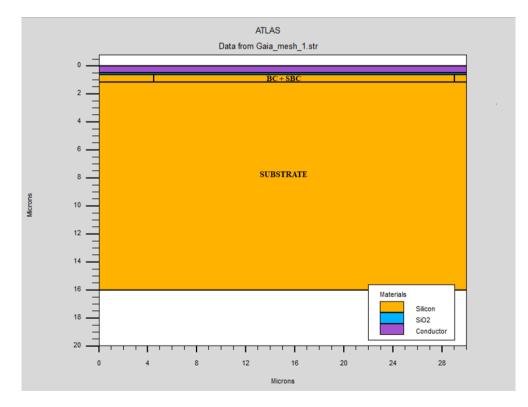


Fig. 4.3: The 2D Gaia AF CCD structure in the AC direction as simulated in

SILVACO ATLAS

4.3 COMPARISON WITH REPORTED EXTERNAL QUANTUM EFFICIENCY

We have elucidated the Gaia AF CCD pixel structure used in our simulations, but to test their efficiency the IQE can be used. To begin with, we have focused on single-layer AR coatings that have been applied on the backside of the CCD (substrate side). The thickness of the AR coating is estimated using the quarter wavelength formula (**Eqn. 4.1**).

AR coating thickness
$$=\frac{\lambda}{4n}$$
 (4.1)

In Eqn. 4.1, λ is the wavelength at which the AR coating is centred, i.e., the wavelength at which the AR coating will allow for maximum photon absorption; n is the refractive index of the AR coating material at the wavelength λ [11]. The SOPRA database of the SILVACO ATLAS software was tremendously helpful in allowing us to include the refractive indices of the AR coatings.

While simulating the pixel structure with the HfO₂ AR coating, the **Eqn. 4.1** deduces the thickness of the coating as 0.085 μ m. We identified the EQE for this setup to benchmark our simulations against the previously published EQE values by [16]. The simulation results are comparable to the experimental results, which can be visualised in **Fig. 4.4**. Any differences in the values of EQE might be because of the absence of ABD in our structure as the parameters required for its simulations were not published in the current literature.

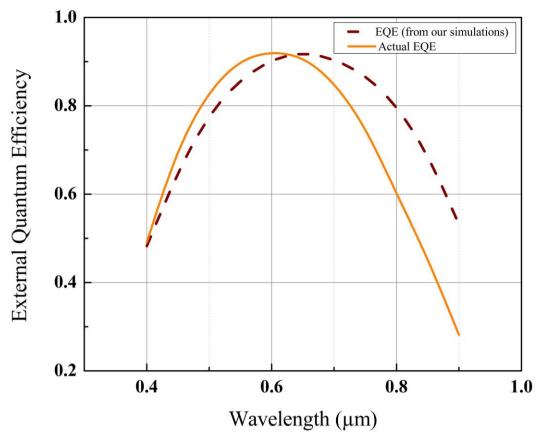


Fig 4.4: Comparison of the actual EQE of the Gaia AF CCDs and the EQE obtained from the simulations

4.4 CONCLUSION

Gaia has provided astronomers with a better eye to view our sparkling galaxy. This would not have been possible without the AF CCDs. We simulated their structure using SILVACO TCAD. The results of the simulations matched with the previously published literature by [16]. This allowed the benchmarking of the simulated model and proved to be a base for further testing to improve the QE of the Gaia AF CCDs.

CHAPTER 5

STUDY OF THE QE OF THE GAIA AF CCD PIXEL MODEL WITH SEVERAL AR COATINGS

The importance of AR coatings for the Gaia AF CCD is unquestionable. The currently used HfO₂ and other materials for coatings have been investigated using the SILVACO TCAD software. The QE of the Gaia AF CCDs with different AR coatings has been determined for the whole spectral range.

5.1 WITH HAFNIUM DIOXIDE

On calculating the IQE for the Gaia AF CCD without applying any AR coating, it was discovered that they have a maximum IQE of 0.65 at the wavelength of 0.7 μ m. Comparing the IQE of the CCDs with and without the HfO₂ coating, we clearly observe an average increment of about 37.2% in the whole wavelength range. **Fig. 5.1** coveys this increment graphically.

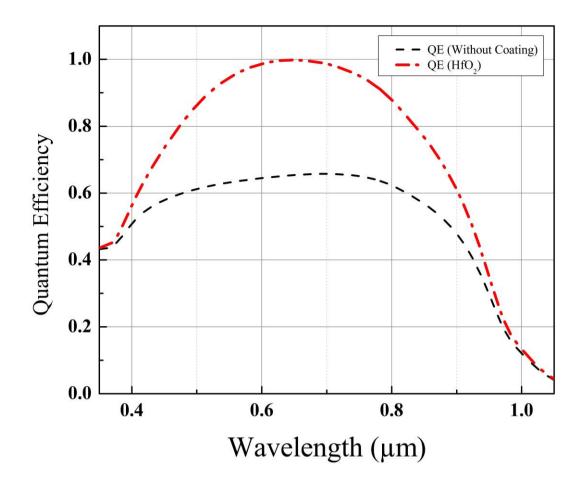


Fig 5.1: QE of the Gaia AF CCD without and with an HfO₂ AR coating

5.2 WITH ZINC SULPHIDE

As per our study of AR coating materials, we choose four AR coatings to test our device. ZnS being one of them. Application of 0.069 μ m thick single layer coating of ZnS, centred at 0.65 μ m, unfolds that it is not very suitable for our device. The IQE curve in **Fig. 5.2** outlines that there is an average decrement of approximately 3.5% when studied parallel to the Gaia AF CCD with a HfO₂ AR coating in the whole range.

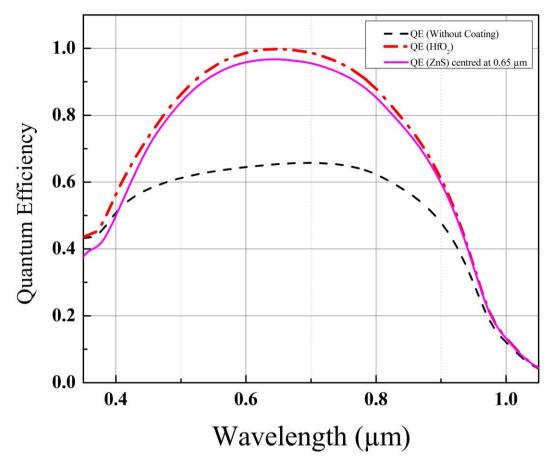


Fig 5.2: QE of the Gaia AF CCD without an AR coating, with an HfO₂ AR coating, and with a ZnS AR coating

5.3 WITH ALUMINIUM OXIDE

Our next choice was Al₂O₃ therefore we applied a single layer of it with a thickness of about 0.098 μ m (calculated as per **Eqn. 4.1**), centred at 0.65 μ m. The Gaia AF CCD with HfO₂ AR coating still provides better results for most wavelengths as compared to Al₂O₃. It is also observed that Al₂O₃ coating provides an average improvement in IQE of about 1.3% in the 0.35 μ m to 0.425 μ m range and an average decrement of about 1.9% in the rest of the wavelength range. These results are compiled in the graph presented in **Fig. 5.3**.

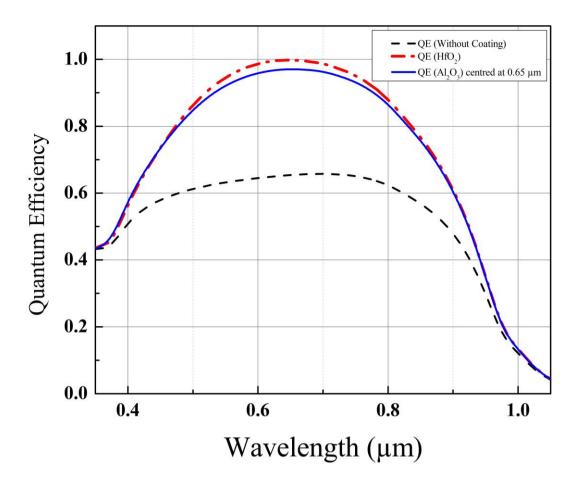


Fig 5.3: QE of the Gaia AF CCD without an AR coating, with an HfO₂ AR coating, and with an Al₂O₃ AR coating

5.4 WITH ZIRCONIUM DIOXIDE

The next alternative that we analysed was a single-layer coating of ZrO_2 centred at 0.65 µm. The thickness of the coating was set as per **Eqn. 4.1** close to 0.073 µm. After observing the graphical data presented in **Fig. 5.4**, we infer that there is an average increment in the IQE of around 0.8% in the range of 0.4 µm to 0.525 µm when analogised with the IQE values when HfO₂ coating was applied. For the rest of the wavelengths, the AR coating of HfO₂ offers an average increment of almost 1.1%, when compared to ZrO₂.

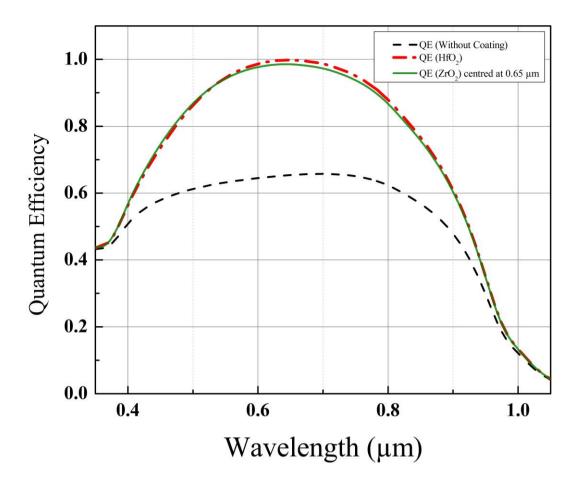


Fig 5.4: QE of the Gaia AF CCD without an AR coating, with an HfO₂ AR coating, and with an ZrO₂ AR coating centred at 0.65 μm

Inspired by the improvements shown by ZrO_2 , we adjusted its thickness to an approximate value of 0.071 µm, which allows for a peak absorbance of the light of wavelength 0.625 µm. This experimentation of ours yields an average increment of nearly 4% for the wavelength range of 0.375 µm to 0.575 µm when compared with HfO₂. with an average compromise of around 2% in the wavelength range of 0.575 µm to 1.05 µm. This data is visualised in **Fig. 5.5**.

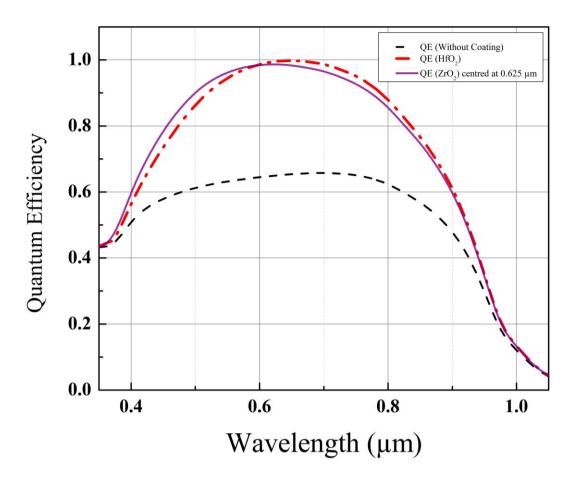


Fig 5.5: QE of the Gaia AF CCD without an AR coating, with an HfO₂ AR coating, and with an ZrO₂ AR coating centred at 0.625 μm

5.5 WITH TANTALUM PENTOXIDE

We concluded our studies with Ta₂O₅ which is a promising AR coating. A single layer of Ta₂O₅, centred at 0.65 μ m with a thickness of approximately 0.09 μ m (calculated using **Eqn. 4.1**) permits almost the same performance as HfO₂. It is evident from **Fig. 5.6** that the two curves virtually overlap each other in the whole range. We did not obtain such promising results for any other AR coating. Hence, to improve the IQE in the low wavelength region, we deposited a 0.086 μ m thick layer of Ta₂O₅ to centre the AR coating at 0.625 μ m. The IQE of the Gaia AF CCDs with an AR coating of Ta₂O₅ shows an average increment of about 2.8% as compared to the CCDs with HfO₂ AR coating in the wavelength range of 0.375 μ m to 0.6 μ m. There is an average decrease of around 1.2% in the IQE of the wavelengths ranging from 0.6 μ m to 1.05 μ m which is clearly evident in **Fig. 5.7**.

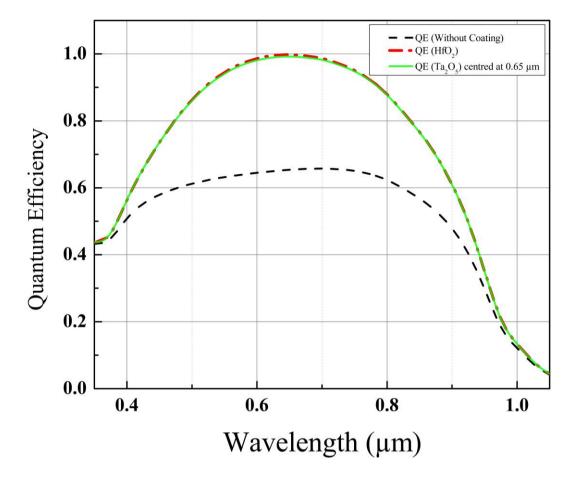


Fig 5.6: QE of the Gaia AF CCD without an AR coating, with an HfO₂ AR coating, and with an Ta₂O₅ AR coating centred at 0.65 μm

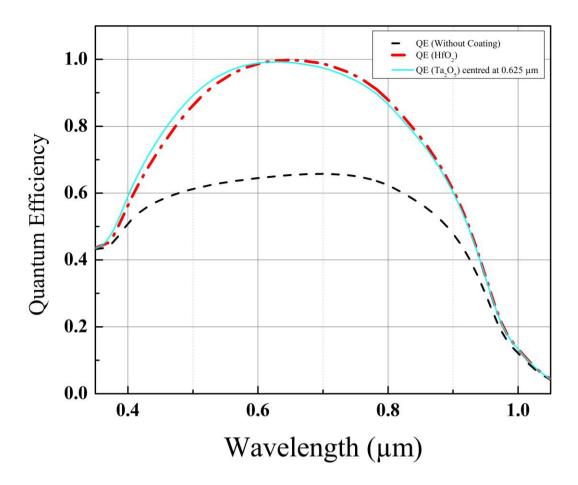


Fig 5.7: QE of the Gaia AF CCD without an AR coating, with an HfO₂ AR coating, and with an Ta₂O₅ AR coating centred at 0.625 μm

5.6 CONCLUSION

A comparative study has been drawn to analyse which AR coating best suits the Gaia AF CCDs. It is observed that a single layer coating of ZrO₂ and Ta₂O₅ gives similar or better results as compared to HfO₂ for most wavelengths lying in Gaia's AF CCD range (330-1050 nm) [22]. **Table 5.1** summarises the comparison among the IQE of CCDs for different AR coatings.

Table 5.1: Percentage increment and decrement in the QE of the Gaia AF CCD with different AR coatings as compared to the HfO₂ AR coating.

| | AR | Wavelength | Percentage Increment/ | Average Increment/ |
|----------------|---|---|--|--|
| S. N. | Coatings | Range (µm) | Decrement | Decrement |
| | | | in the IQE | in the IQE |
| 1. | HfO2 | 0.33 – 1.05 | Increment (2.6% to 53.3%) as compared to a CCD without any AR coating | Increment (37.2%) as compared to a CCD without any AR coating |
| 2. | ZnS (centred at 0.65 μm) | 0.35 – 1.05 | Decrement (0.3% to 12.2%) as compared to HfO ₂ | Decrement (3.5%) as compared to HfO ₂ |
| 3. | Al ₂ O ₃ (centred | 0.35 – 0.425 | Increment (0.1% to 2.3%) as compared to HfO ₂ | Increment (1.3%) as compared to HfO ₂ |
| at 0.65 μm) | 0.425-1.05 | Decrement (0.09% to 2.8%) as compared to HfO ₂ | Decrement (1.9%) as compared to HfO ₂ | |
| 4. | 4. ZrO ₂ (centred at 0.65 μm) | 0.4 - 0.525 | Increment (0.04% to 1.35%) as compared to HfO ₂ | Increment (0.8%) as compared to HfO ₂ |
| т. | | 0.525 -1.05 | Decrement (0.19% to 1.4%) as compared to HfO ₂ | Decrement (1.1%) as compared to HfO ₂ |

| 5. | 5. ZrO ₂ (centred at 0.625 μm) | 0.375 – 0.575 | Increment (0.63% to 6.85%) as compared to HfO ₂ | Increment (4%) as compared to HfO ₂ |
|----|---|------------------|--|--|
| | | 0.575 – 1.05 | Decrement (0.38% to 2.72%) as compared to HfO ₂ | Decrement (2%) as compared to HfO ₂ |
| 6. | Ta ₂ O ₅ (centred at 0.65 | 0.35 – 0.9 | Decrement (0.64% and less) as compared to HfO ₂ | No prominent change as compared to HfO2 |
| | μm) | 0.9 - 1.05 | Increment (0.04% and less) as compared to HfO ₂ | No prominent change as compared to HfO2 |
| 7. | Ta2O5 (centred at | 0.375 – 0.6 | Increment (0.17% to 5.15%) as compared to HfO ₂ | Increment (2.8%) as compared to HfO ₂ |
| | 0.625 μm) | 0.6 - 1.05 | Decrement (0.19% to 1.57%) as compared to HfO ₂ | Decrement (1.2%) as compared to HfO ₂ |

CHAPTER 6

ANALYSIS OF GALLIUM NITRIDE AS AN ALTERNATIVE TO SILICON FOR ASTRONOMICAL CCDs

The importance of radiation in astronomy is paramount. It is the one single physical quantity that governs the oldest science. It is advertently clear from the above studies that even with suitable AR coatings a silicon detector is unsuitable for low (< 500 nm) and high (> 800 nm) wavelength regions of the operational spectrum of the Gaia AF CCDs.

There can be several reasons for this, but the two main factors responsible for silicon's behaviour in these regions are its high reflectivity and low absorption coefficient.

It has been described in the previous chapters that in order to have a better absorption coefficient for the CCD the material from which the CCD substrate is made has to be deeply deliberated over. The properties of the material chosen should be such that it offers low reflectivity and a high absorption coefficient, while also performing electrically well.

6.1 IMPORTANCE OF IMAGINARY REFRACTIVE INDEX

The absorption coefficient is perhaps the most important of the parameters defined in **Chapter 2** for the quantum efficiency of a CCD. The reason for this can be understood from the graphs in **Fig. 6.1**.

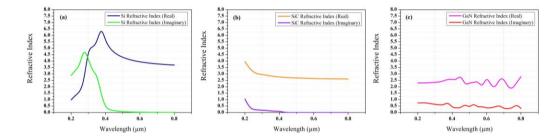


Fig. 6.1: The real (n) and imaginary refractive indices (k) of (a) silicon, (b) silicon carbide (SiC), and (c) gallium nitride (GaN) in the wavelength range of 0.2 μ m to 0.8 μ m.

SILVACO TCAD's SOPRA database has been used for the plots in Fig. 6.1 [18, 19]. It can be comprehended from Fig. 6.1 (a) that the value of k decreases sharply for silicon until about 0.4 μ m and assumes an extremely small value thereafter. This implies that silicon has a very small value of absorption coefficient after 0.4 μ m. The absorption coefficient of a material at a specific wavelength can be calculated as per Eqn. 2.2, for silicon they have been calculated and are presented in Fig. 3.7.

It can be observed in **Fig. 6.1 (a)**, (b), and (c) that along with a small absorption coefficient the reflectivity of silicon will be quite high above 0.4 μ m when compared to SiC and GaN because of its high value of n. For the wavelength range below 0.4 μ m until 0.2 μ m the value of n for silicon is substantially higher in contrast to SiC and GaN. This means that silicon will provide a higher reflectivity in this range in comparison to SiC and GaN. The average reflectivity of silicon in the wavelength range of 0.2 μ m to 0.45 μ m is about 47 %. Furthermore, due to a large variation in the real refractive index curve in **Fig. 6.1 (a)** in this range, it is hard to find a suitable AR coating to reduce such reflectivity, as refractive index matching is essential for them as described in **Section 3.1.2**. Hence, silicon does not prove to be a very good photodetector in high (> 800 nm) and low (< 500 nm) wavelength ranges.

A similar trend for the complex refractive index of SiC can be observed in **Fig. 6.1 (b)**, but with much less values of n in the wavelength range of $0.2 \,\mu\text{m}$ – 0.4 μm in comparison to silicon. This makes SiC highly suitable for lowwavelength photodetectors [30-34], but for broadband detectors like the Gaia AF CCDs, these desirable properties are required for a much larger wavelength range. This can be seen for GaN in **Fig. 6.1 (c)**.

6.2 SUITABILITY OF GaN FOR BROADBAND ASTRONOMICAL CCDs

As evident from **Fig. 6.1 (c)** and the above discussion, the suitability of GaN for broadband astronomical CCDs can be attributed to its comparatively low values of n and higher values of k in a broadband wavelength range. It can be expected from GaN that it will help to achieve low reflectivity and a high absorption coefficient in the whole operational wavelength range of the Gaia AF CCDs. It also has superior conductivity when compared to silicon [35].

The major reason why GaN is only used for low wavelength applications is because of its high bandgap and radiation hardness properties [35-41]. The bandgap of GaN at room temperature is about 3.3 eV [26]. Compared to silicon's bandgap of about 1.1 eV it is quite large [26]. For a broadband CCD a bandgap near to or less than silicon's bandgap is required, so that photogeneration can take place. To reduce the bandgap of GaN for its use in broadband astronomical CCDs, the bandgap narrowing property of a semiconductor can be used, which is directly related to the doping concentration [35, 39].

6.3 SIMULATION AND CALCULATIONS FOR THE GaN CCD PIXEL STRUCTURE

To simulate the GaN CCD pixel structure and compare its performance with the silicon Gaia AF CCD pixel structure the dimensions of both models have been set to the same values. The Gaia AF CCD pixel structure parameters used for the simulations are mentioned in **Table 4.1**. The only differences between the two models are that for the GaN structure, the doping values have been varied and GaN is used instead of silicon for the n-type and p-type layers, other parameters such as temperature, operating potential, etc. remain the same for the simulation of both the models.

The n-type doping concentration used for GaN is 1.00×10^{21} cm⁻³, and the p-type doping concentration has been set to 8.9×10^{19} cm⁻³. These values have been carefully set to cause sufficient band gap narrowing. The narrowed bandgap values of the GaN model for n-type and p-type substrates have been calculated using the equations mentioned in [18, 19, 35, 39].

6.4 COMPARISON OF THE GaN CCD MODEL WITH THE GAIA AF CCD MODEL

The first step to propose GaN as an alternative to silicon for broadband astronomical CCDs is to test and compare their electrical performance. The potential profiles of the silicon pixel and the GaN pixel models have been presented in **Figs. 6.2** and **6.3** respectively. The Tonyplot tool of the SILVACO software has been used to generate them.

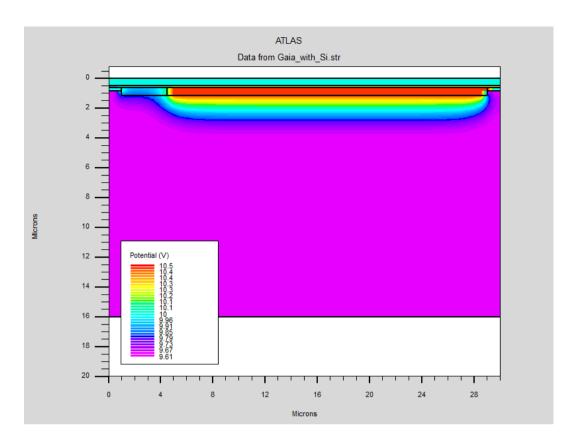


Fig. 6.2: The potential variation of the silicon Gaia AF CCD pixel model

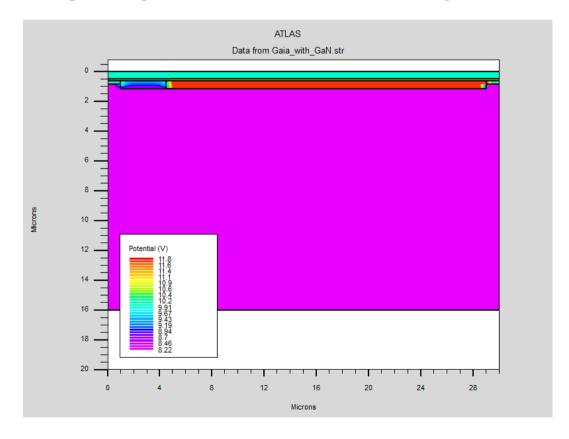


Fig. 6.3: The potential variation of the GaN pixel model

It can be observed after comparing the above two figures that the maximum and minimum potentials for the silicon pixel model are 10.5 V and 9.61 V respectively. They are 11.8 V and 8.22 V for the GaN pixel model. This demonstrates that their electrical performances are in close comparison to each other.

To test the optical performance of both the models their IQE and EQE with and without suitable AR coatings have been calculated and compared in **Figs. 6.4 (a), (b), and (c)**. The thickness of the AR coating for the GaN model has been set to 86.3 nm and for the silicon model to about 85 nm. The coating materials and their thickness for both models have been derived from the studies presented in **Chapter 3**.

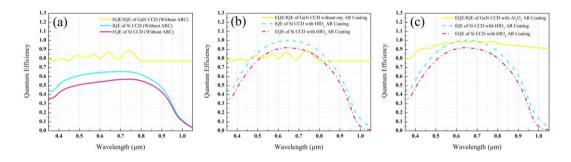


Fig. 6.4: Comparison of the IQE and EQE of the GaN model with the silicon pixel model when they are simulated (a) Without any AR coatings, (b) with only silicon model with an HfO₂ coating, and (c) with GaN model with an Al₂O₃ AR coating and silicon model with an HfO₂ AR coating

The optical performance of the GaN model is as expected and much better than the silicon model in all three cases. When their optical performance is compared without any AR coatings the GaN pixel model provides an average increment of about 84.6 % in the EQE. An average increment of about 31.2 % is observed even when the GaN pixel structure without any AR coating is compared with the silicon model with an HfO₂ AR coating. Finally, when both the models with an AR coating are compared, the average increment offered by the GaN pixel has been determined as 52.8 %. For the GaN model, the differences in the EQE and IQE are very minute, of the order of 10⁻³. These negligible differences can be attributed to the fact that GaN has a better conductivity than silicon and after using the doping values mentioned above its conductivity increases even more [35]. For the silicon model, the doping values are not very high and hence the difference between its EQE and IQE is observed.

6.5 CONCLUSION

In astronomical parlance, the increment in the EQE and IQE values offered by the GaN pixel model is quite substantial. While the silicon-based broadband pixel model needs an AR coating to compete with an uncoated GaN pixel model, the GaN pixel still increases the QE by almost a third of the QE offered by the silicon model. Hence, the GaN CCDs can be used without an AR coating and still provide better results. This would also mean that long deliberations for an AR coating material for an astronomical CCD can be eliminated, saving time and simplifying the fabrication process. Even with such a substantial increment in the QE, GaN does not lag in its electrical performance. Hence, GaN can prove to be the future of astronomical CCDs and pave the path for a better exploration of the universe.

CHAPTER 7

CONCLUSION AND FUTURE SCOPE OF THIS WORK

We tested our Gaia AF CCD pixel model against the actual EQE values reported by Walker et al. (2008) using the Monte Carlo simulations of the SILVACO TCAD software. This has been done to ensure the accuracy of our simulations. It can be evidently seen in **Fig 4.4** that there are some differences between the experimental observations and our simulations. These deviations in the results might be attributed to the absence of SBC and ABD in our structure since these features are proprietary to e2v.

We studied the Gaia AF CCDs and tested them with various AR coatings to enhance their QE values. Our simulations establish that AR coatings are an important factor in improving the IQE and EQE of astronomical CCDs. They also elucidate that Ta₂O₅ and ZrO₂ are better materials for astronomical CCDs than HfO₂, mainly in the spectrum region from 0.330 μ m to 0.575 μ m. ZnS and Al₂O₃, although appear to be promising materials yet do not prove to be very efficient in enhancing the Gaia AF CCDs QE values.

Furthermore, due to the low absorption coefficient of silicon and large reflection losses in almost the whole operation of the Gaia AF CCDs GaN has been analysed electrically and optically to be considered as an alternative to silicon for broadband astronomical CCDs. The GaN CCDs can prove to be substantially better than the silicon CCDs due to their superior optical and electrical performance.

This work has important implications for the development of astronomical CCDs, which will help them to obtain the best possible data from satellites and telescopes. Multi-layer AR coatings and the use of GaN as a material for the CCD substrate can be deliberated for this purpose in the future which can enhance our knowledge of the Milky Way and the universe even more. In this work, we focused on the optical losses of astronomical CCDs. For future studies, other losses of the CCDs such as dark current, trap formation, etc., can also be interpreted in depth which will help astronomers work in the direction of irradicating these losses and making CCDs more efficient and increasing their usefulness.

REFERENCES

- [1] N. Alfaraj, "A review of charge-coupled device image sensors," *University* of Toronto: Toronto, ON, Canada, 2017.
- [2] M. Lesser, "Charge coupled device (CCD) image sensors," in *High Performance Silicon Imaging*: Elsevier, 2014, pp. 78-97.
- [3] M. Lesser, "A summary of charge-coupled devices for astronomy," *Publications of the Astronomical Society of the Pacific*, vol. 127, no. 957, pp. 1097-1104, 2015.
- [4] H. Rongqing, "Chapter 4 Photodetectors," in *Introduction to Fiber-Optic Communications*, H. Rongqing Ed.: Academic Press, 2020, pp. 125-154.
- [5] I. Lundstrm, "Hydrogen sensitive MOS-structures: part 1: principles and applications," *Sensors and actuators,* vol. 1, pp. 403--426, 1981.
- S. E. Holland, D. E. Groom, N. P. Palaio, R. J. Stover, and W. Mingzhi, "Fully depleted, back-illuminated charge-coupled devices fabricated on high-resistivity silicon," *IEEE Transactions on Electron Devices*, vol. 50, no. 1, pp. 225-238, 2003, doi: 10.1109/TED.2002.806476.
- [7] G. E. Smith, "Nobel Lecture: The invention and early history of the CCD," *Reviews of modern physics*, vol. 82, no. 3, p. 2307, 2010.
- [8] S. A. Taylor, "CCD and CMOS imaging array technologies: technology review," *UK: Xerox Research Centre Europe*, pp. 1-14, 1998.
- [9] R. H. Walden, R. H. Krambeck, R. J. Strain, J. McKenna, N. L. Schryer, and G. E. Smith, "B.S.T.J. brief: The buried channel charge coupled device," *The Bell System Technical Journal*, vol. 51, no. 7, pp. 1635-1640, 1972, doi: 10.1002/j.1538-7305.1972.tb02674.x.
- [10] B. E. Burke and S. A. Gajar, "Dynamic suppression of interface-state dark current in buried-channel CCDs," *IEEE Transactions on Electron Devices*, vol. 38, no. 2, pp. 285-290, 1991, doi: 10.1109/16.69907.

- [11] M. Lesser, "Antireflection coatings for silicon charge-coupled devices," *Optical Engineering*, vol. 26, no. 9, pp. 911--921, 1987.
- [12] P. D. Omodeo, "Geocentrism," in *Encyclopedia of Renaissance Philosophy*: Springer International Publishing, 2016, pp. 1-6.
- [13] H. R. Devi, O. Y. Bisen, S. Nanda, R. Nandan, and K. K. Nanda, "Internal versus external quantum efficiency of luminescent materials, photovoltaic cells, photodetectors and photoelectrocatalysis.," *Current Science* (00113891), vol. 127, no. 7, 2021.
- [14] M. Born and E. Wolf, Principles of optics: electromagnetic theory of propagation, interference and diffraction of light. Elsevier, 2013.
- [15] E. Hecht, "Optics 5th edn (England," ed: Pearson, 2017.
- [16] A. Walker *et al.*, "The Gaia challenge: Testing high performance CCDs in large quantities," 2008.
- [17] T. Prusti *et al.*, "The gaia mission," *Astronomy* \& *astrophysics*, vol. 595, p. A1, 2016.
- [18] A. U. Manual, "Silvaco International," *Santa Clara, CA*, vol. 95054, p. 23, 2000.
- [19] I. Silvaco, "ATLAS user's manual device simulation software," Santa Clara, CA, 2010.
- [20] C. Crowley *et al.*, "Gaia data release 1-On-orbit performance of the Gaia CCDs at L2," *Astronomy* & *Astrophysics*, vol. 595, p. A6, 2016.
- [21] J. H. J. De Bruijne, "Science performance of Gaia, ESA's space-astrometry mission," *Astrophysics and Space Science*, vol. 341, no. 1, pp. 31--41, 2012.
- [22] G. Seabroke, A. Holland, and M. Cropper, "Modelling radiation damage to ESA's Gaia satellite CCDs," 2008.
- [23] G. M. Seabroke, A. D. Holland, D. Burt, and M. S. Robbins, "Modelling electron distributions within ESA's Gaia satellite CCD pixels to mitigate radiation damage," 2009.
- [24] G. Seabroke, A. Holland, D. Burt, and M. Robbins, "Silvaco ATLAS model of ESA's Gaia satellite e2v CCD91-72 pixels," 2010.
- [25] G. M. Seabroke, T. Prod'homme, G. Hopkinson, D. Burt, M. Robbins, andA. Holland, "Modelling Gaia CCD pixels with Silvaco 3D engineering

software," *European Astronomical Society Publications Series*, vol. 45, pp. 433--436, 2010.

- [26] W. Strehlow and E. L. Cook, "Compilation of energy band gaps in elemental and binary compound semiconductors and insulators," *Journal of Physical* and Chemical Reference Data, vol. 2, no. 1, pp. 163-200, 1973.
- [27] J. Krupka, J. Breeze, A. Centeno, N. Alford, T. Claussen, and L. Jensen, "Measurements of permittivity, dielectric loss tangent, and resistivity of float-zone silicon at microwave frequencies," *IEEE Transactions on microwave theory and techniques*, vol. 54, no. 11, pp. 3995-4001, 2006.
- [28] R. K. Chanana, "On the work function of metals and the electron affinity of crystal surfaces of semiconductors," *Journal of Electrical and Electronics Engineering*, vol. 17, no. 5, pp. 09-12, 2022.
- [29] D. V. Melnikov and J. R. Chelikowsky, "Electron affinities and ionization energies in silicon and Ge nanocrystals," *Physical Review B*, vol. 69, no. 11, p. 113305, 2004.
- [30] A. Aldalbahi *et al.*, "A new approach for fabrications of SiC based photodetectors," *Scientific Reports*, vol. 6, no. 1, p. 23457, 2016.
- [31] A. Gottwald, U. Kroth, E. Kalinina, and V. Zabrodskii, "Optical properties of a Cr/4H-SiC photodetector in the spectral range from ultraviolet to extreme ultraviolet," *Applied Optics*, vol. 57, no. 28, pp. 8431-8436, 2018.
- [32] M. L. Megherbi et al., "An Efficient 4H-SiC photodiode for UV sensing applications," *Electronics*, vol. 10, no. 20, p. 2517, 2021.
- [33] F. Moscatelli, "Silicon carbide for UV, alpha, beta and X-ray detectors: Results and perspectives," *Nuclear Instruments and Methods in Physics Research Section A: Accelerators, Spectrometers, Detectors and Associated Equipment*, vol. 583, no. 1, pp. 157-161, 2007.
- [34] V. Sankin, P. Shkrebiy, and N. Savkina, "Silicon carbide ultraviolet photodetectors," in *International Semiconductor Device Research Symposium*, 2003, 2003: IEEE, pp. 130-131.
- [35] D. K. Saini, "Gallium nitride: Analysis of physical properties and performance in high-frequency power electronic circuits," Wright State University, 2015.

- [36] N. Aggarwal and G. Gupta, "Enlightening gallium nitride-based UV photodetectors," *Journal of Materials Chemistry C*, vol. 8, no. 36, pp. 12348-12354, 2020.
- [37] O. Al-Zuhairi *et al.*, "Non-polar gallium nitride for photodetection applications: A systematic review," *Coatings*, vol. 12, no. 2, p. 275, 2022.
- [38] H. S. Alpert *et al.*, "Gallium nitride photodetector measurements of UV emission from a gaseous CH4/O2 hybrid rocket igniter plume," in 2019 IEEE Aerospace Conference, 2019: IEEE, pp. 1-8.
- [39] K. N. Chopra, "A Technical Note on Gallium Nitride Technology and short Qualitative Review of its Novel Applications," *Lat. Am. J. Phys. Educ. Vol*, vol. 8, no. 3, p. 541, 2014.
- [40] Z. Fan, "An analysis of GaN-based ultraviolet photodetector," in *IOP Conference Series: Materials Science and Engineering*, 2020, vol. 738, no. 1: IOP Publishing, p. 012006.
- [41] H. D. Jabbar, M. A. Fakhri, and M. J. AbdulRazzaq, "Gallium nitride–based photodiode: a review," *Materials Today: Proceedings*, vol. 42, pp. 2829-2834, 2021.

DECLARATION

I hereby declare that the work which is presented in the Dissertation-II Project entitled "Quantum Efficiency of Astronomical Charge-coupled Devices for Deeper Exploration of our Cosmos" in the partial fulfilment of the requirement for the award of the Degree of Masters in Science and submitted to the Department of Applied Physics, Delhi Technological University, Delhi is an authentic record of my own, carried out during a period from August 2022 to May 2023, under the co-supervision of Prof. (Dr.) Nitin K. Puri and Dr. George M. Seabroke.

The matter presented in this thesis has not been submitted by me for the award of any other degree of this or any other Institute/ University. The work has been accepted and communicated in SCI/SCI Expanded indexed journals with the following details:

Title of Paper 1: Diving deep into the Milky Way using Anti-Reflection Coatings for Astronomical CCDs

Author names (in sequence as per research paper): Anmol Aggarwal, Ashi Mittal, George M. Seabroke, Nitin K. Puri
Name of Journal: Journal of Astrophysics and Astronomy
Status of Paper (Accepted/Published/Communicated): Accepted
Date of paper communication: 28th December 2022
Date of paper acceptance: 7th May 2023

Title of Paper 2: Gallium Nitride: The future cornerstone of broad range astronomical CCDs

Author names (in sequence as per research paper): Anmol Aggarwal, George M. Seabroke, Nitin K. Puri

Name of Journal: Experimental Astronomy

Status of Paper (Accepted/Published/Communicated): Communicated (Awaiting first report)

Date of paper communication: 27th July 2023

NMOL AGGARWAL 2K21/MSCPHY/55

SUPERVISOR CERTIFICATE

To the best of our knowledge, the above work has not been submitted in part or full for any Degree or Diploma to this University or elsewhere. We further certify that the publication and indexing information given by the students is correct.

(Prof. Nitin K. Puri)

Place: Delhi

Date: 3.º May 2023



Place: Newbury, United Kingdom

(Dr. George M. Seabroke)

Date: 30 May 2023

NOTE: PLEASE ENCLOSE THE RESEARCH PAPER ACCEPTANCE/ PUBLICATION/COMMUNICATION PROOF ALONG WITH SCI INDEXING PROOF

LIST OF PUBLICATIONS

Title of Paper 1: Diving deep into the Milky Way using Anti-Reflection Coatings for Astronomical CCDs Author names (in sequence as per research paper): Anmol Aggarwal, Ashi Mittal, George M. Seabroke, Nitin K. Puri Name of Journal: Journal of Astrophysics and Astronomy Status of Paper (Accepted/Published/Communicated): Accepted Date of paper communication: 28th December 2022 Date of paper acceptance: 7th May 2023

Title of Paper 2: Gallium Nitride: The future cornerstone of broad range astronomical CCDs Author names (in sequence as per research paper): Anmol Aggarwal, George M. Seabroke, Nitin K. Puri

Name of Journal: Experimental Astronomy

Status of Paper (Accepted/Published/Communicated): Communicated (Awaiting first report)

Date of paper communication: 27th July 2023

ACCEPTANCE PROOF

Paper 1: Diving deep into the Milky Way using Anti-Reflection Coatings for Astronomical CCDs

5/27/23, 11:03 PM Gmail - Fwd: JOAA: Your manuscript entitled Diving deep into the milky way using Anti-Reflection Coatings for Astronomical ...



Ashi Mittal <ashimittal2000@gmail.com>

Fwd: JOAA: Your manuscript entitled Diving deep into the milky way using Anti-Reflection Coatings for Astronomical CCDs - [EMID:e43e6a967c22a3ff]

Dr. Nitin Puri <nitinkumarouri@dtu.ac.in> 15 May 2023 at 12:19 To: Ashi Mittal <ashimittal2000@gmail.com>, Anmol Aggarwal <stjadelhi@gmail.com> Forwarded message From: Annapurni Subramaniam <em@editorialmanager.com> Date: Monday, May 8, 2023 Subject: JOAA: Your manuscript entitled Diving deep into the milky way using Anti-Reflection Coatings for Astronomical CCDs - [EMID:e43e6a967c22a3ff] To: "Nitin K. Puri" <nitinkumarpuri@dtu.ac.in> Ref : Ms. No. JOAA-D-22-00278R1 Diving deep into the milky way using Anti-Reflection Coatings for Astronomical CCDs Journal of Astrophysics and Astronomy Dear Prof. Puri, I am glad to inform you that your paper mentioned above has been accepted for publication in The Journal of Astrophysics and Astronomy. The details are as follows: Accepted 07 May 2023. Revised 09 Apr 2023. In original form 28 Dec 2022. Regards, Chief Editor Comments for the Author: Reviewer #1: The changes previously suggested were carefully addressed and I do recommend the paper for publication. In compliance with data protection regulations, you may request that we remove your personal registration details at any time. (Use the following URL: https://www.editorialmanager.com/joaa/login.asp?a=r). Please contact the publication office if you have any questions. Dr. Nitin K. Puri Professor, Department of Applied Physics Associate Dean (Outreach and Extension Activities) Delhi Technological University (DTU) (Formerly Delhi College of Engineering, DCE)

Govt. of NCT of Delhi Shahbad Daulatpur, Main Bawana Road, Delhi-110042, India <u>Email:</u> nitinkumarpuri@dtu.ac.in <u>www.dtu.ac.in</u>

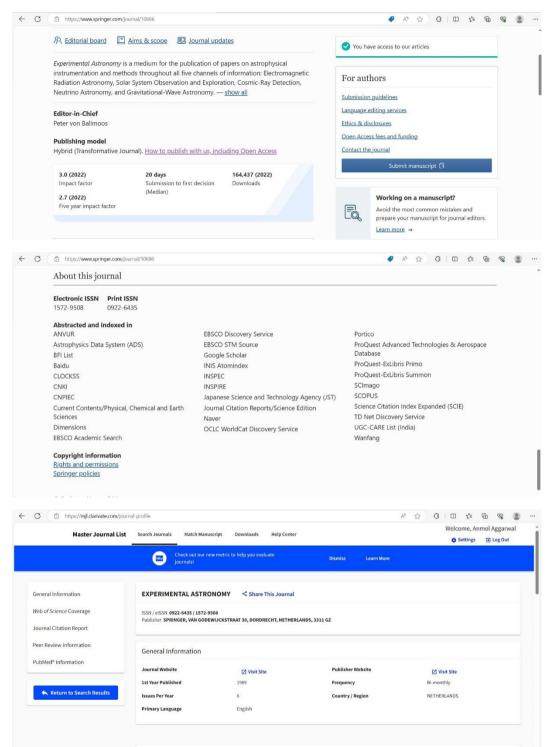
https://mail.google.com/mail/u/0/?ik=a6dede7621&view=pt&search=all&permthid=thread-f:1765941802071750957&simpl=msg-f:1765941802071... 1/1

JOURNAL INDEXING PROOF

Journal 1

| ← → C ☆ ⓐ springer.com/journal/12 | 2036 | | | G 🖻 🖈 🖪 🖪 | |
|---|--|--|--|--|--|
| | | | | | |
| Go-published by Inco of India | | d Astronomy ences and Astronomical Society | | | |
| रे Editorial board 🛛 🔳 Aims & scor | <u>oe</u> | | ✓ You have access | to our articles | |
| Published by the Indian Academy of | Sciences | | | | |
| litor-in-Chief | | | For authors | | |
| Annapurni Subramaniam | | | Submission guideline | | |
| iblishing model Ibscription | | | Ethics & disclosures | | |
| (Media | sion to first decision | 25,255 (2021) Downloads | <u>Contact the journal</u> Su | ibmit manuscript (구 Activate Windows | |
| 1.766 (2021) Five year impact factor | | | | Go to Settings to activate Windows. | |
| | | | | • .* | |
| → C ☆ | 2036 | | | G 🖻 🛧 🗯 🗖 🄇 | |
| ectronic ISSN 973-7758 | | | | | |
| p-Publisher information p-publication with Indian Academy o sit Co-Publisher Site: <u>Astronomical S</u> | | | | | |
| | <u>ociety of India, Indian</u> | Academy of Sciences | | | |
| ostracted and indexed in trophysics Data System (ADS) | EBSCO | Discovery Service | Portico | | |
| l List | | Engineering Source | ProQuest Advanced Technologies & Aerospace Database | | |
| idu OCKSS | | STM Source | | ProQuest-ExLibris Primo | |
| IKI | | Science & Technology Collection Scholar | | Libris Summon | |
| IPIEC | | omindex | SCImago | | |
| emical Abstracts Service (CAS) | INSPEC | Shindex | SCOPUS | | |
| rrent Contents/Physical, Chemical a | | | Science Citat | ion Index | |
| ences | | e Science and Technology Agency | (JST) Science Citat | ion Index Expanded (SCIE) | |
| mensions | | Citation Reports/Science Edition | TD Net Disco | | |
| SCO Academic Search | Naver | citation reports/science Earlion | UGC-CARE List (India) ivate Windows | | |
| SCO Britannica Online Collection | | /orldCat Discovery Service | Wanfang | | |
| → C ☆ â mjl.clarivate.com/journa | al-profile | | | G 🖻 🖈 🖬 🌘 | |
| General Information | | HYSICS AND ASTRONOMY | ihare This Journal | | |
| Web of Science Coverage | JORNAL OF ASTROPT | | and this southat | | |
| | SN / eISSN 0250-6335 / 0973-7 blisher INDIAN ACAD SCIENCI | 758 ES, C V RAMAN AVENUE, SADASHIVANAGAR, P | B #8005, BANGALORE, INDIA, 5 | 60 080 | |
| Peer Review Information | | | | | |
| G | eneral Information | | | | |
| Return to Search Results | blisher Website | ☑ Visit Site | 1st Year Published | 1980 | |
| Fn | equency | Continuous publication | Issues Per Year | 1 | |
| Co | untry / Region | INDIA | Primary Language | English | |
| | | | | | |
| W | eb of Science Coverag | e | | | |
| | Collection Inde | ex | Category | Similar Journals ⁹ Activate Windows | |
| | Core Collection Scie | nce Citation Index Expanded (SCIE) | Astronomy & Astrophysics | Go to Settings to activate Window Q Find Similar Journals | |

Journal 2



PLAGIARISM REPORT

🔊 turnitin Similarity Report ID old 27535-36355986 PAPER NAME Thesis_merged_Anmol_merged.pdf WORD COUNT CHARACTER COUNT 9426 Words 45801 Characters PAGE COUNT 52 Pages 1.9MB SUBMISSION DATE REPORT DATE May 28, 2023 6:43 PM GMT+5:30 May 28, 2023 6:43 PM GMT+5:30 7% Overall Similarity The combined total of all matches, including overlapping sources, for each database. 4% Publications database 4% Internet database · Crossref Posted Content database Crossref database · 4% Submitted Works database Excluded from Similarity Report Bibliographic material Ounted material · Small Matches (Less then 8 words) Cited material Summary G. M. Jeabrike Dr. George M. Seabroke Prof. (Dr.) Nitin K. Puri Co-supervisor Supervisor Ashiblital Ashi Mittal Anmol Aggarwal 2K21/MSCPHY/07 2K21/MSCPHY/55

ACCEPTED RESEARCH ARTICLE

| | J. Astrophys. Astr################################### | © Indian Academy of Sciences | |
|----------|--|---|----|
| 2 | | Check for updates | |
| 3 | Diving deep into the milky way using anti | -reflection coatings for astronomical | |
| 4 | CCDs | • | |
| 5 | ANMOL AGGARWAL ¹ , ASHI MITTAI | 1 GEORGE M SEARPOKE2 and | |
| 5 | NITIN K. PURI ^{1,*} | , GEORGE M. SEABROKE and | |
| 7 | ¹ Advanced Sensor Laboratory and Nanomater | als Research Laboratory, Department of Applied Physics, | |
| 8 | Delhi Technological University, Delhi 110042. | | |
| 9 | ² Mullard Space Science Laboratory, Departme | ant of Space and Climate Physics, Faculty of Maths and | |
| 10 | Physical Sciences, University College, London *Corresponding author. E-mail: nitinkumarpur | | |
| 12 | -corresponding autior, E-mail, munkumarpur | word, av. m, munpuri2002 wyan00.00.m | |
| 13 | MS received 28 December 2022; accepted 8 M | fay 2023 | |
| 14 | Abstract. We report two anti-reflection (AR) | coatings that give better quantum efficiency (9QE) than the | |
| 15 | | d (AF) charged coupled devices (CCDs). Light being the core | |
| 16 | of optical astronomy, which is extremely impo | rtant for such missions, therefore, the QE of the devices that | |
| 17 | | the the losses due to the reflection of light from the | |
| 18 | | ed. Currently, the main component of the Gaia satellite, the | |
| 19 20 | | ating. In this paper, the ATLAS module of the SILVACO and studying the AF CCD pixel structure and several AR | |
| 21 | | lioxide (ZrO_2) and tantalum pentoxide (Ta_2O_3) will prove to | |
| 22 | | mical CCDs in the future and will open new avenues to | |
| 23 | understand the evolution of the milky way. | | |
| 24 | | | |
| 25 26 | Keywords, gaia—sILVACO TCAD—astrono reflection coatings. | omical instrumentation-charged coupled devices-anti- | |
| | | | |
| 27 | 1. Introduction | for different wavelength ranges (De Bruijne 2012). | 4 |
| 28 | To annich astronomy with man anning a | The AF CCDs are built using silicon (Si) as a substrate | 4 |
| 28 29 | To enrich astronomy with more precise measure- ments, the European Space Agency (ESA) launched | with an anti-reflection (AR) coating, which has a maximum photon absorption for a light of 650 nm; | 4 |
| 30 | Gaia Satellite in the L2 orbit in December 2013. Its | this CCD has an extensive wavelength detection range | 4 |
| 31 | two telescopes keep an eye on millions of stars, | of 330–1050 nm (Seabroke et al. 2008). There are 78 | 5 |
| 32 | galaxies and solar system objects to produce high- | AF CCDs on the Gaia focal plane, which are 16 µm | 5 |
| 33 | precision astrometric and spectroscopic measurements | thick (Crowley et al. 2016). The BP and RP are | 5 |
| 34 | (Prusti et al. 2016). The continuous scan gives data | enhanced CCDs that have exceptional sensitivity | 5 |
| 35 | sets that are repeatedly reduced to calculate the par- | towards the blue (330-680 nm) and red (640-1050 | 5 |
| 36 | allax, position and proper motion of the celestial | nm) regions of the light spectrum, respectively. Seven | 5 |
| 37 | objects that are observed by the satellite (Crowley | BP CCDs present on the Gaia focal plane, have the | 50 |
| 38 39 | et al. 2016). The focal plane of the Gaia satellite | maximum photon absorption for the light of 360 nm because of its AP coating (Crowley at al. 2016) | 5 |
| 40 | contains 106 custom-built charged coupled devices (CCDs). These CCDs were designed and manufac- | because of its AR coating (Crowley et al. 2016). Correspondingly, seven RP CCDs have the maximum | 51 |
| +0 41 | tured by e2v technologies, UK (Walker et al. 2008). | photon absorption for the light of 750 nm (Crowley | 6 |
| 42 | Gaia CCDs were fabricated by e2v in three different | et al. 2016). These CCDs have an image area of 4500 | 6 |
| 43 | variants: Astrometric field (AF), red photometer (RP) | lines \times 1966 columns (here, lines and columns, refer | 6 |
| 14 | and blue photometer (BP); each of these are optimized | to the rows and columns of the pixels of the CCD, | 6 |
| | | | |
| | fournal - Large 12036 Article No. : 9962 | Dispatch : 74-2023 Pages : 9 | |
| | MS Code - 100A-D-22-00278R1 | CP CP DISK | |

Page 2 of 9

respectively) (De Bruijne 2012). A schematic diagram 64 65 of the arrangement of CCDs on the actual Gaia focal 66 plane is shown in figure 1. The detectors are operating in the time delay and integration mode with a period 67 68 of 982.8 µs, which synchronizes their line transfer rate 69 with the satellite rotation rate (Crowley et al. 2016; De Bruijne 2012). In Gaia parlance, line transfer means 70 71 electrons being transferred in a row of pixels (Crowley 72 et al 2016)

73 As the name suggests, AR coatings are essentially 74 important in improving the internal quantum efficiency (IQE) of the CCDs because they play a vital 75 role in enhancing their photon absorption by reducing 76 77 the losses due to the reflection of incident light. The 78 IQE is used as a measuring stick to determine the 79 performance of an AR coating, which is the ratio of the number of photons that enter the CCD to the 80 number of photons incident on the device (Devi et al. 81 82 2012). The external quantum efficiency (EQE) is the ratio of the number of photoelectrons generated to the 83 number of photons incident on the CCD (Devi et al. 84 85 2012). Since the Gaia CCDs generally do not get a lot of time to capture the incoming light from distant 86 objects, their IQE should be substantially high. An AR 87 coating is a thin layer of high refractive index material 88 89 (Lesser 1987). It also acts as a line of defence for the 90 CCDs (Lesser 1994).

91 The Gaia AF CCDs have been analysed since they 92 cover the maximum area (78 out of 106 CCDs) of the 93 Gaia focal plane and capture the widest wavelength 94 range. Studies that amalgamate AR coatings and 95 astronomical CCDs have been conducted. IQE of the

96 device has been deliberated, which in fact is directly

proportional to the EQE of the device. Several AR 97 coatings for the Gaia AF CCDs have been scrutinized 98 to enhance this factor using the SILVACO software. 99

2. Simulations and calculations

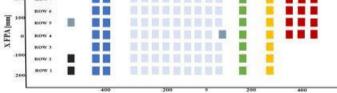
100

SILVACO TCAD is used to simulate several electronic and optical devices. It uses numerical methods 102 for simulations so that the development and optimization of such devices can be expedited. For simulating the effects of AR coatings on an optoelectronic 105 device, the LUMINOUS and the ATLAS modules of 106 this software can be used. 107

Since the Gaia AF CCDs are back-illuminated 108 devices, the AR coatings are applied on the backside. 109 Photons are also fired on this side in our simulations. 110 The operating voltage was set to 10 V as suggested by 111 Seabroke et al. (2009). In SILVACO simulations, the 112 ratio of available current density (Javailable) and source 113 current density (J_{source}) gives the IQE of a device. The 114 number of photoelectrons generated in a device can be 115 determined using the electron current density (J_n) . 116

We simulated an AF CCD pixel in 2-dimensions 117 (2D) using SILVACO, our aim is to obtain IQE of the 118 device with various AR coatings at different wave-119 lengths. We assessed several materials as AR coat-120 ings, namely, hafnium dioxide (HfO2), aluminum 121 oxide (Al₂O₃), zinc sulfide (ZnS), zirconium dioxide 122 (ZrO₂) and tantalum pentoxide (Ta₂O₅). Although an 123 AR coating of HfO2 is already present on the AF 124 CCDs (Short et al. 2005), which gives impressive 125 results. We suspected that there was a scope of 126





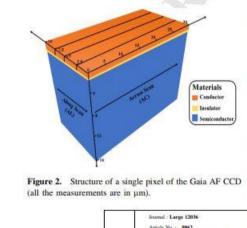
Y FPA [mm]

Figure 1. Gaia focal plane has 106 CCDs arranged in seven different rows. The red rectangles represent radial velocity spectrometers (RVS). The green and yellow rectangles depict blue and red photometers (BP and RP), respectively, while the grey and black rectangles show wavefront sensors (WFS) and basic angle monitors (BAM), respectively. The light blue rectangles depict the most abundant i.e., AF CCDs and the dark blue rectangles are called sky mappers (SM). The SM and the WFS are also AF CCDs. The RVS and BAM have a constructions similar to the RP.

| 1 | Journal : Large 12036 | Dispatch : 7-6-2023 | Pages: 9 |
|---|-----------------------------|---------------------|-----------|
| | Article No. : 9962 | D LE | D TYPESET |
| ~ | MS Code : JOAA-D-22-00278R1 | of CP | M DISK |

improvement in IOE of the devices. Our simulations 127 proclaim that EQE of the Gaia AF CCDs with this AR 128 129 coating peaks at 650 nm with a value of 0.99. Simu-130 lating these CCDs without any AR coating revealed 131 that there is a large increase of 37.2% in the IQE when AR coatings are applied on such devices. Hence, AR 132 133 coatings can be regarded as a cornerstone of astro-134 nomical CCDs 135 A CCD is essentially a MOS-based device, which 136 acts as an image detector. In MOS, the letter M stands 137 for metal, the letter O stands for oxide and the letter S 138 stands for semiconductor (Lundström 1981). Therefore, the structure of CCD consists of a layer of 139 140 metallic electrodes placed on a thin insulating layer 141 lined over a semiconductor substrate. Lundström (1981) reports details of the MOS structure. CCDs are 142 of two types, front-illuminated and back-illuminated. 143 144 In the former, light is incident on the electrodes, while the light is incident on the semiconductor substrate in 145 the latter (Lesser 2014, 2015). The back-illuminated 146 147 CCDs are constructed in actual practice because they 148 offer a larger surface area for photogeneration and 149 photon absorption than front-illuminated CCDs (Lesser 2015). 150

151 For simulating the Gaia AF CCD pixel in SIL-VACO, several structural parameters were required, 152 which were derived from (Seabroke et al. 153 2008, 2009, 2010; Seabroke et al. 2010). The pixel 154 155 structure of the CCD has three different faces, which is evident from figure 2. We simulated the structure in 156 157 the across scan (AC) direction in 2D with a pixel size of 16 µm × 30 µm. The 16 µm thickness of the pixel 158 is subdivided into multiple layers, the details of which 159 160 are summarized in Table 1.



Page 3 of 9 _####_

The Gaia AF CCD entails a lot of interesting 161 structural intricacies, namely, buried channel (BC), 162 supplementary buried channel (SBC) and anti-163 blooming drain (ABD) (Seabroke et al. 2008). A BC 164 is formed near a p-n junction by placing a thin layer 165 of negatively doped Si on a positively doped substrate. 166 This channel has no free charges and is used to hold 167 the photogenerated electrons before they are read out. 168 A photon incident on a CCD creates an electron-hole 169 pair; the electron thus generated, then moves to the 170 BC 171

The SBC is a support feature to the BC but is no 172 less functional. When the number of photogenerated 173 electrons exceeds the capacity of the SBC, they spill 174 into the BC which holds them until they are read out 175 (Seabroke et al. 2010, 2013). The length of BC and 176 SBC runs from 4.5 to 29 µm in the AC direction 177 (Seabroke et al. 2010). The ABD, which is present on 178 either side of the pixel in the AC direction is a 179 shielding feature. It prevents the electrons from 180 divulging into the adjacent pixel (Seabroke et al. 181 2010). Now, to simulate all these interesting features 182 in SILVACO, the whole AF CCD image pixel was 183 modeled with uniform doping as suggested by Seab-184 roke et al. (2009). 185

The Gaia AF CCDs work at a temperature of 163 K 186 (Seabroke et al. 2008) to minimize the dark current, 187 which is attributed to the false positive signals pro-188 duced in the CCD due to the thermal energy of elec-189 trons (Lesser 2015). Therefore, to match our 190 theoretical simulations with the experimental results 191 reported by Walker et al. (2008), we conducted our 192 simulations at the same temperature. 193

To simulate the CCD pixel structure, the SILVACO 194 ATLAS package uses some constants for the simulated materials that are handled internally. It uses the Monte Carlo method to model the structure. Table 2 197 compares the experimental values of the constants 198 with the values used during our simulations. 199

Figure 3 exhibits the simulated structure of the Gaia 200 AF CCD pixel; the illustration was generated using 201 the TonyPlot tool of the SILVACO software. 202

2.1 AR coatings

We have elucidated the Gaia AF CCD pixel structure 204 used in our simulations, but to test their efficiency, the 205 IQE can be used. To begin with, we have focused on 206 single-layer AR coatings that have been applied on the 207 backside of the CCD (substrate side). The thickness of 208

203

| Journal : Large 12036 | Dispatch : 7-6-2023 | Pages: 9 |
|-----------------------------|---------------------|----------|
| Article No. : 9962 | D LE | TYPESET |
| MS Code : JOAA-D-22-00278R1 | CP CP | Z DISK |

Page 4 of 9

Table 1. Thickness and doping densities of different layers in the AF CCD pixel structure (Seabroke et al. 2009).

| S. no. | Material | Туре | Thickness (µm) | Doping density (cm ⁻³) |
|--------|------------------------|---------------|----------------|------------------------------------|
| 1 | Polycrystalline Si | Conductor | 0-0.5 | 0 |
| 2 | Silicon dioxide (SiO2) | Insulator | 0.5-0.63 | 0 |
| 3 | N-type Si | Semiconductor | 0.63-1.17 | 2.65×10^{16} |
| 4 | P-type Si | Semiconductor | 1.17-16 | 1.3×10^{14} |

| S. no. | Name of constant | Theoretical values used in SILVACO ATLAS | Experimental values |
|-----------|-------------------------------------|---|---|
| 1. | Energy gap of Si (E_g) | 1.08 eV at 300 K 1.11 eV at 163 K | 1.12 eV at 300 K (Strehlow & Cook 1973) |
| 2. | Relative permittivity of Si (Er) | 11.8 at 300 K 11.8 at 163 K | 11.66 at 300 K (Krupka et al. 2006) |
| 3. | Electron affinity of Si (X) | 4.17 eV at 300 K 4.16 eV at 163 K | 4.05 eV at 300 K (Melnikov & Chelikowsky 2004) Chanana 2022) |
| 4. | Temperature (T) | 163 K | 163 K (Seabroke et al. 2008) |

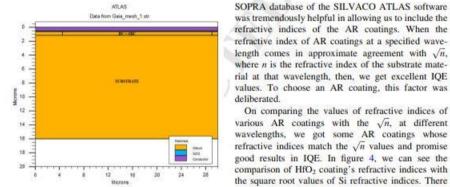


Figure 3. 2D Gaia AF CCD structure in the across scan (AC) direction as simulated in SILVACO ATLAS.

209 the AR coating is estimated using the quarter wavelength formula (Equation 1). 210

AR coating thickness = $\frac{\kappa}{4n}$

212 In Equation (1), λ is the wavelength at which the 213 AR coating is centered, i.e., the wavelength at which 214 the AR coating will allow for maximum photon 215 absorption; n is the refractive index of the AR coating

216

material at the wavelength λ (Lesser 1987). The

was tremendously helpful in allowing us to include the 218 refractive indices of the AR coatings. When the 219 refractive index of AR coatings at a specified wave-220 221 length comes in approximate agreement with \sqrt{n} , where n is the refractive index of the substrate mate-222 rial at that wavelength, then, we get excellent IQE 223 values. To choose an AR coating, this factor was 224 deliberated. 225 On comparing the values of refractive indices of 226

217

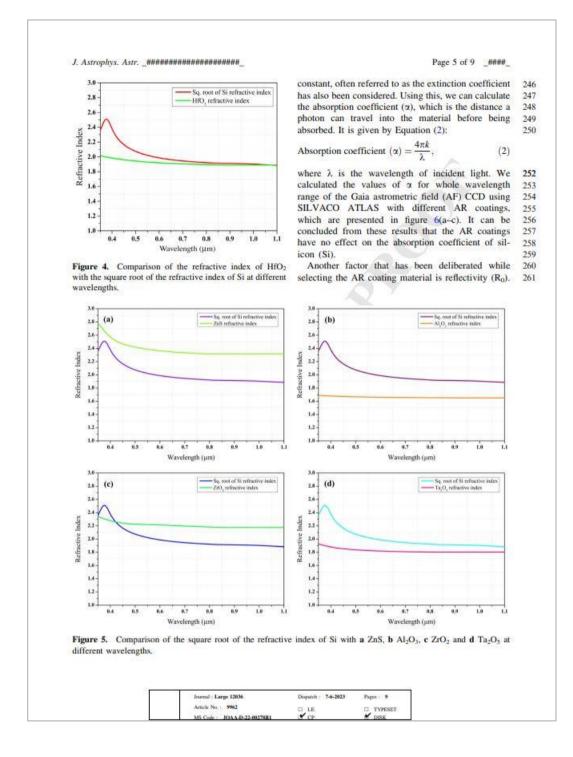
various AR coatings with the \sqrt{n} , at different 227 wavelengths, we got some AR coatings whose 228 refractive indices match the \sqrt{n} values and promise 229 good results in IQE. In figure 4, we can see the 230 comparison of HfO2 coating's refractive indices with 231 the square root values of Si refractive indices. There 232 is a very good matching which evidently explains 233 why this AR coating is used in designing the Gaia 234 AF CCDs. 235

On performing the same comparison with various 236 AR coatings, we got some promising results from 237 ZnS, Al₂O₃, ZrO₂ and Ta₂O₅, which can be seen in 238 figure 5. Figure 5a shows how similar the values of 239 \sqrt{n} of Si and the refractive index of ZnS. Figure 5b 240 shows that the refractive index of Al2O3 is also close 241 to the \sqrt{n} of Si values. Figure 5c and d show similar 242 results for ZrO2 and Ta2O5. 243

While choosing the materials for AR coatings, their 244 imaginary refractive index, which is a complex optical 245

| Journal - Large 12036 | Dispatch : 7-6-2023 | Pages : 9 |
|-----------------------------|---------------------|-----------|
| Article No. : 9962 | II LE | TYPESET |
| MS Code = JOAA-D-22-00278R1 | CP CP | M DISK |

(1)



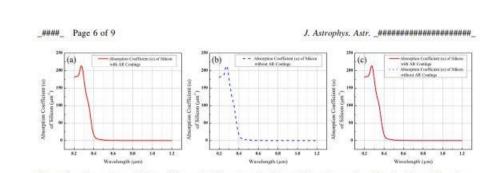


Figure 6. Absorption coefficient of Si: a with AR coatings, b without AR coatings and c with and without AR coatings.

262 Equation (3) is used to calculate the reflectivity of a 263 surface using the real refractive indices:

$$\text{Reflectivity}(R_0) = \left| \frac{n_1 - n_2}{n_1 + n_2} \right|^2, \quad (3)$$

265 where n_1 and n_2 are the real refractive indices (at a 266 specific wavelength) of the medium from which the 267 light is incident and the AR coating material, respectively. The reflectivity of the Si-air interface is 268 largely affected by the optical properties of AR 269 270 coating materials. The effect of AR coatings on the reflectivity of the Si-air interface is presented in fig-271 ure 7, which has been calculated using the SILVACO 272 273 ATLAS software.

For an AR coating to perform well, its respective refractive indices of the AR coating material also should be in approximate agreement with the square root of the respective refractive indices of the substrate material (\sqrt{n}), as per Lesser (1987). Ta₂O₅ 279 satisfies this condition, is the best among all the

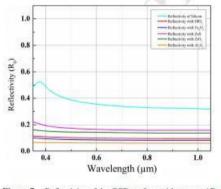


Figure 7. Reflectivity of the CCD surface without any AR coating and with different AR coatings.

studied AR coating materials, and reduces the reflec-280 tivity substantially. Hence, it can be concluded that 281 Ta₂O₅ can be proven to be the best AR coating 282 material for our case. Although Al2O3 reduces the 283 reflectivity to the least value compared to all the 284 studied AR coatings, as presented in figure 7, its 285 respective refractive indices are not very close to the 286 square root of the respective refractive indices of Si 287 (figure 5b), which might hinder its performance. 288

3. Results and discussion

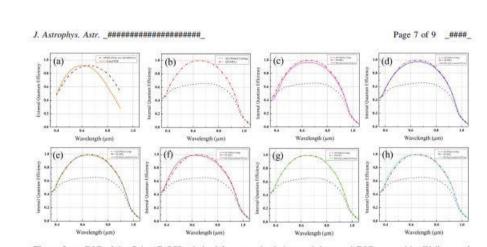
While simulating the pixel structure with the HfO2 AR 290 coating, Equation (1) deduces the thickness of the 291 coating to 0.085 µm. We identified the EQE for this 292 setup to benchmark our simulations against the pre-293 viously published EQE values by Walker et al. (2008). 294 The simulation results are comparable to the experi-295 mental results, which can be visualized in figure 8(a). 296 Any differences in the values of EQE might be 297 because of the absence of ABD in our structure, as the 298 parameters required for its simulations were not 299 published in the current literature. 300

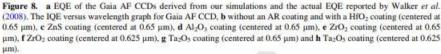
289

On calculating IQE for the Gaia AF CCD without 301 applying any AR coating, it was discovered that they 302 have a maximum IQE of 0.65 at the wavelength of 0.7 μ m. Comparing the IQE of the CCDs with and without 304 the HfO₂ coating, we clearly observed an average 305 increment of about 37.2% in the whole wavelength 306 range. Figure 8b coveys this increment graphically. 307

As per our study of AR coating materials, we 308 choose four AR coatings to test our device. One of 309 them is ZnS. Application of 0.069 µm thick single-310 layer coating of ZnS, centered at 0.65 µm, unfolds that 311 it is not very suitable for our device. The IQE curve in 312 figure 8c outlines that there is an average decrement of 313 ~3.5% when studied parallel to the Gaia AF CCD 314 with a HfO2 AR coating in the whole range. 315

| Journal - Large 12036 | Disputch : 7-6-2023 | Pages : 9 |
|-----------------------------|---------------------|-----------|
| Article No. : 9962 | D LE | I TYPESET |
| MS Code : JOAA-D-22-00278R1 | er ce | DISK |





316 Our next choice was Al₂O₃. Therefore, we applied a single layer of it with a thickness of about 0.098 µm 317 (calculated as per Equation 1), centered at 0.65 µm. 318 319 The Gaia AF CCD with HfO2 AR coating still pro-320 vides better results for most wavelengths as compared 321 to Al2O3. It is also observed that Al2O3 coating pro-322 vides an average improvement in IQE of about 1.3% 323 in the 0.35-0.425 µm range and an average decrement 324 of about 1.9% in the rest of the wavelength range. These results are compiled in the graph presented in 325 326 figure 8d. 327 The next alternative that we analysed was a single-

328 layer coating of ZrO2 centered at 0.65 µm. The thickness of the coating was set as per Equation (1) 329 330 close to 0.073 µm. After observing the graphical data 331 presented in figure 8e, we infer that there is an average increment in the IQE of around 0.8% in the range of 332 0.4-0.525 µm when analogized with the IQE values 333 334 when HfO2 coating was applied. For the rest of the 335 wavelengths, the AR coating of HfO2 offers an aver-336 age increment of almost 1.1%, when compared to 337 ZrO, Inspired by the improvements shown by ZrO2, we 338

adjusted its thickness to an approximate value of
 0.071 µm, which allows for a peak absorbance of the
 light of wavelength of 0.625 µm. Our experimentation
 on this, yields an average increment of nearly 4% for
 the wavelength range of 0.375–0.575 µm when

 compared with HfO₂, with an average compromise of around 2% in the wavelength range of 0.575–1.05 μm.
 344

 This data is visualized in figure 8f.
 346

347 We concluded our studies with Ta₂O₅, which is a promising AR coating. A single layer of Ta2O5, cen-348 tered at 0.65 µm with a thickness of ~0.09 µm (cal-349 culated using Equation 1), permits almost the same 350 performance as HfO2. It is evident from figure 8g that 351 the two curves virtually overlap each other in the 352 whole range. We did not obtain such promising results 353 for any other AR coating. Hence, to improve the IQE 354 in the low wavelength region, we deposited a 0.086 355 um thick layer of Ta2O5 to the center of the AR 356 coating at 0.625 µm. The IQE of the Gaia AF CCDs 357 with an AR coating of Ta2O5 shows an average 358 increment of about 2.8% compared to the CCDs with 359 HfO2 AR coating in the wavelength range of 360 0.375-0.6 µm. There is an average decrease of around 361 1.2% in IQE of the wavelengths ranging from 0.6 µm 362 to 1.05 µm, which is clearly evident in figure 8h. 363

A comparative study has been drawn to analyse, 364 which AR coating best suits the Gaia AF CCDs. It is 365 observed that a single layer coating of ZrO2 and 366 Ta2O5 gives similar or better results as compared to 367 HfO2 for most wavelengths lying in Gaia's AF CCD 368 range (330-1050 nm) (Seabroke et al. 2008). Table 3 369 summarizes the comparison among the IQE of CCDs 370 for different AR coatings. 371

| Journal : Large 12036 | Dispatch : 7-6-2023 | Pages: 9 |
|---------------------------------|---------------------|-----------|
| Article No. : 9962 | II LE | D TYPESET |
| MS Cede : JOAA-D-22-00278R1 | CP CP | DISK. |

Page 8 of 9

Table 3. Percentage increment and decrement in QE of the Gaia AF CCD with different AR coatings as compared to the HfO₂ AR coating.

| S. no. | AR coatings | Wavelength range (µm) | Percentage increment/decrement in IQE | Average increment/decrement in IQE |
|-----------|---|--------------------------|--|--|
| 1. | HfO ₂ | 0.33-1.05 | Increment (2.6–53.3%) as compared to a CCD without any AR coating | Increment (37.2%) as compared to a CCD without any AR coating |
| 2. | ZnS (centered at 0.65 µm) | 0.35-1.05 | Decrement (0.3-12.2%) as compared to HfO ₂ | Decrement (3.5%) as compared to HfO ₂ |
| 3. | Al ₂ O ₃ (centered at 0.65 µm) | 0.35-0.425 | Increment (0.1-2.3%) as compared to HfO ₂ | Increment (1.3%) as compared to HfO ₂ |
| | | 0.425-1.05 | Decrement (0.09-2.8%) as compared to HfO ₂ | Decrement (1.9%) as compared to HfO ₂ |
| 4. | ZrO ₂ (centered at 0.65 µm) | 0.4-0.525 | Increment (0.04–1.35%) as compared to HfO ₂ | Increment (0.8%) as compared to HfO ₂ |
| | | 0.525-1.05 | Decrement (0.19-1.4%) as compared to HfO ₂ | Decrement (1.1%) as compared to HfO ₂ |
| 5. | ZrO ₂ (centered at 0.625 μm) | 0.375-0.575 | Increment (0.63-6.85%) as compared to HfO ₂ | Increment (4%) as compared to HfO2 |
| | | 0.575-1.05 | Decrement (0.38-2.72%) as compared to HfO ₂ | Decrement (2%) as compared to HfO2 |
| 6. | Ta ₂ O ₅ (centered at 0.65 µm) | 0.35-0.9 | Decrement (0.64% and less) as compared to HfO ₂ | No prominent change as compared to HfO ₂ |
| | | 0.9-1.05 | Increment (0.04% and less) as compared to HfO ₂ | No prominent change as compared to HfO ₂ |
| 7. | Ta2O5 (centered at 0.625 µm) | 0.375-0.6 | Increment (0.17-5.15%) as compared to HfO ₂ | Increment (2.8%) as compared to HfO ₂ |
| | | 0.6-1.05 | Decrement (0.19-1,57%) as compared to HfO ₂ | Decrement (1.2%) as compared to HfO ₂ |

372 4. Conclusions

373 We tested our Gaia AF CCD pixel model against the actual EQE values reported by Walkeret al. (2008), 374 which indicated the accuracy of our simulations. We 375 376 presented our studies of the Gaia AF CCDs with 377 various AR coatings to enhance the QE values. Any 378 deviations in the results might be attributed to the absence of SBC and ABD in our structure since these 379 features are proprietary to e2v. The performance of an 380 AR coating can also be determined using a simple Si 381 382 wafer. But, to validate our results for astronomical 383 CCDs, we used an electrical model in SILVACO 384 ATLAS. This allows our results to be more accept-385 able to the astronomical community. 386 Our simulations establish that AR coatings are an important factor in improving the IQE and EQE of 387 astronomical CCDs. They also elucidate that Ta2O5 388 389 and ZrO2 are better materials for astronomical CCDs 390 than HfO2, mainly in the spectrum region from 0.330 391 µm to 0.575 µm. Hence, this work has important 392 implications for the development of astronomical

CCDs, which will help them to obtain the best possible data from satellites and telescopes. Multi-layer 394 AR coatings can be deliberated for this purpose in the future, which might enhance our knowledge of the milky way even more. 397

398

407

Acknowledgments

We are grateful to Prof. Ashutosh Bharadwaj, Univer-399 sity of Delhi, for his help and motivation throughout 400 this research. We are also thankful to Dr Harsupreet 401 Kaur for providing us with the license for TCAD 402 SILVACO ATLAS 2021 software. We gratefully 403 acknowledge Ms. Ritika Khatri, Delhi Technological 404 University, for her continuous support and guidance 405 during this research. 406

References

Chanana R. K. 2022, Journal of Electrical and Electronics 408 Engineering 17, 09 409

| Journal - Large 12836 | Disputch : 7-6-2023 | Pages: 9 |
|---------------------------------|---------------------|-----------|
| Article No. : 9962 | I LE | D TYPESET |
| MS Code : JOAA-D-22-00278R1 | 2 CP | C DISK |

| 410 | J. Astrophys. Astr#################################### | Page 9 of 9 _####_ | |
|--|---|---|--|
| 411 412 413 414 415 416 417 418 419 420 421 422 423 424 425 426 427 428 | Crowley C., Kohley R., Hambly N. C. et al. 2016, A&A 595, A6 De Bruijne J. 2012, Ap&SS 341, 31 Devi H. R., Bisen O. Y., Nanda S., Nandan R., Nanda K. K. 2021, Current Science 00113891, 127 Krupka J., Breeze J., Centeno A. et al. 2006, IEEE Transactions on Microwave Theory and Techniques 54, 3995 Lesser M. 1987, Optical Engineering 26, 911 Lesser M. 2015, PASP 127, 1097 Lesser M. 2015, PASP 127, 1097 Lesser M. P. 1994, in Instrumentation in Astronomy VIII, Vol. 2198, SPIE, p. 782 Lundström I. 1981, Sensors and Actuators 1, 403 Melnikov D. V., Chelikowsky J. R. 2004, Physical Review B 69, 113305 Prusti T., De Bruijne J., Brown A. G. et al. 2016, A&A 595, A1 Seabroke G., Holland A., Burt D., Robbins M. 2009, in Astronomical and Space Optical Systems, Vol. 7439, SPIE, p. 35 | Seabroke G., Holland A., Burt D., Robbins M. 2010, in High Energy, Optical, and Infrared Detectors for Astron- omy IV, Vol. 7742, SPIE, p. 339 Seabroke G., Holland A., Cropper M. 2008, in High Energy, Optical, and Infrared Detectors for Astronomy III, Vol. 7021, SPIE, p. 515 Seabroke G., Prod'homme T., Hopkinson G., et al. 2010, European Astronomical Society Publications Series, 45, 433 Seabroke G., Prod'homme T., Murray N., et al. 2013, MNRAS, 430, 3155 Short A., Hopkinson G., Laborie A., et al. 2005, in Focal Plane Arrays for Space Telescopes II, Vol. 5902, SPIE, p. 31 Strehlow W., Cook E. L. 1973, Journal of Physical and Chemical Reference Data 2, 163 Walker A., Eaton T., Steward R., et al. 2008, in Sensors, Systems, and Next Generation Satellites XII, Vol. 7106, SPIE, p. 390 | 42 43 43 43 43 43 43 43 43 43 43 44 44 44 |
| | | | 44 |
| | | | |
| | | | |
| | | | |
| | | | |
| | Const | | |
| | Stores | | |

COMMUNICATED RESEARCH ARTICLE

Gallium Nitride: The future cornerstone of broad range astronomical CCDs

Anmol Agganual (ORCID ID: 0000-0003-3666-8873), George M. Seabroka (ORCID ID: 0000-0003-4072-9536), Nitin K. Duri (ORCID ID: 0000-0003-2563-3747)

^e Advanced Sensor Laboratory & Nanomaterials Research Laboratory, Department of Applied Physics, Delhi Technological University, Delhi, 110042, India.

^b Mullard Space Science Laboratory, Department of Space & Climate Physics, Faculty of Maths & Physical Sciences, University College, London, RH5 6NT, United Kingdom.

*Corresponding Author, email id: nitinkumarpuri@dtu.ac.in, nitinpuri2002@yahoo.co.in

Abstract

All astronomical missions use charge-coupled devices (CCDs) as vital organs. Usually, silicon (Si) is selected to build them, which does not perform well without enhancements such as anti-reflection (AR) coatings. Such devices exhibit poor performance in the high (> 800 nm) and low (< 500 nm) wavelength ranges even with AR coatings. We present studies that signify gallium nitride (GaN) as a replacement for silicon (Si) in astronomical CCDs that operate in a wide wavelength range. For this purpose, SILVACO TCAD software has been employed, which has been used for simulating and comparing a GaN CCD pixel with a Gaia astrometric field (AF) CCD pixel. Our observations demonstrate that the optical performance of the GaN based CCD pixel is remarkably better than the Si-based AF CCD pixel. These findings can prove to be the bedrock of future astronomical exploration and wide-range astronomical CCDs, as they allow for an exceptionally high quantum efficiency (QE) even without any reinforcements.

Keywords: Astronomical instrumentation, Gaia, Charge-coupled devices, Quantum Efficiency, Optics

Statements and Declarations

Competing Interests: The authors have no relevant financial or non-financial interests to disclose. Funding: The authors declare that no funds, grants, or other support were received during the preparation of this manuscript.

1